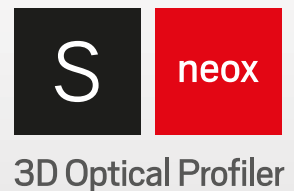


# SENSOFAR METROLOGY



Engineered for Speed  
QA/QC and R&D Solution



# Simply powerful

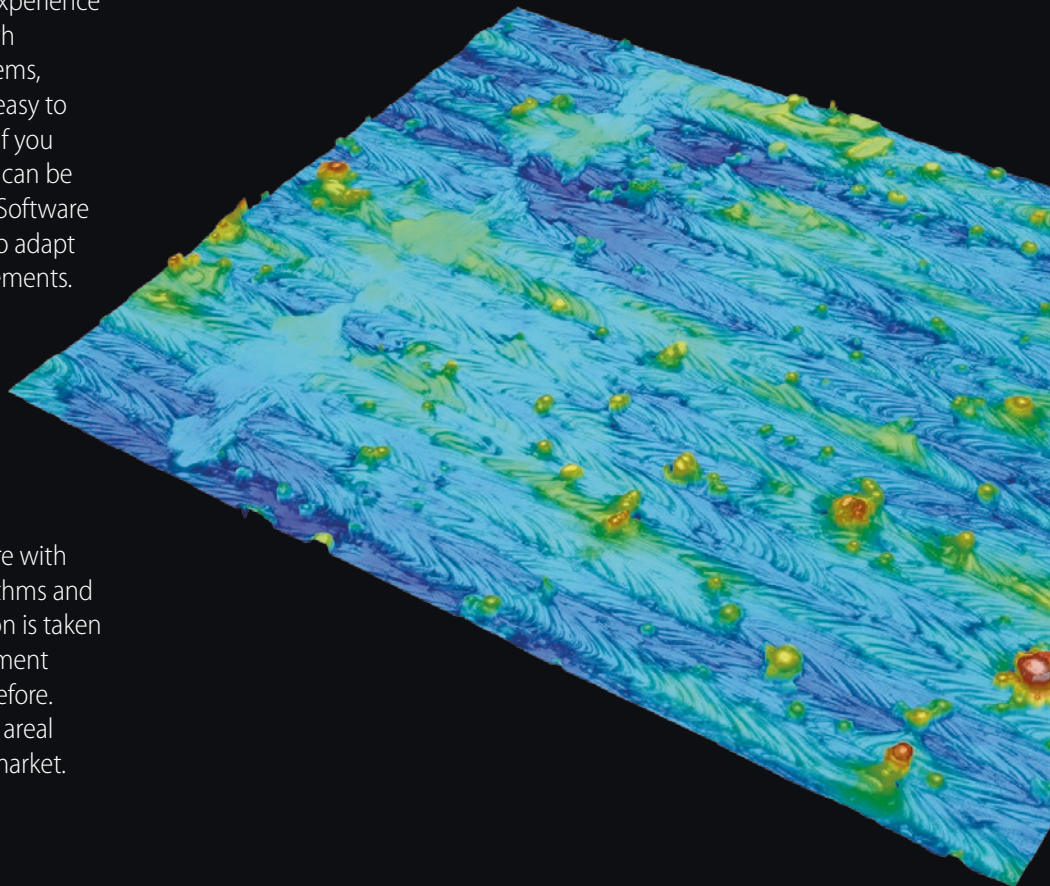
The new S neox outperforms existing optical 3D profiling microscopes in terms of performance, functionality, efficiency and design, providing Sensofar with a class-leading areal measurement system.

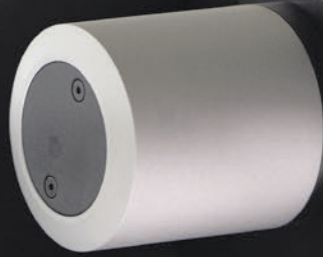
## Easy-to-use

Sensofar is continuously working to provide the most incredible experience to our customers. With the fifth generation of the S neox systems, the goal has been to make it easy to use, intuitive and faster. Even if you are beginner user, the system can be managed with just one click. Software modules have been created to adapt the system to the user requirements.

## Faster than ever

Everything is faster than before with new smart and unique algorithms and a new camera. Data acquisition is taken at 180 fps. Standard measurement acquisition is 5X faster than before. Making the S neox the fastest areal measurement system in the market.





SENSOFAR.  
METROLOGY

## Markets

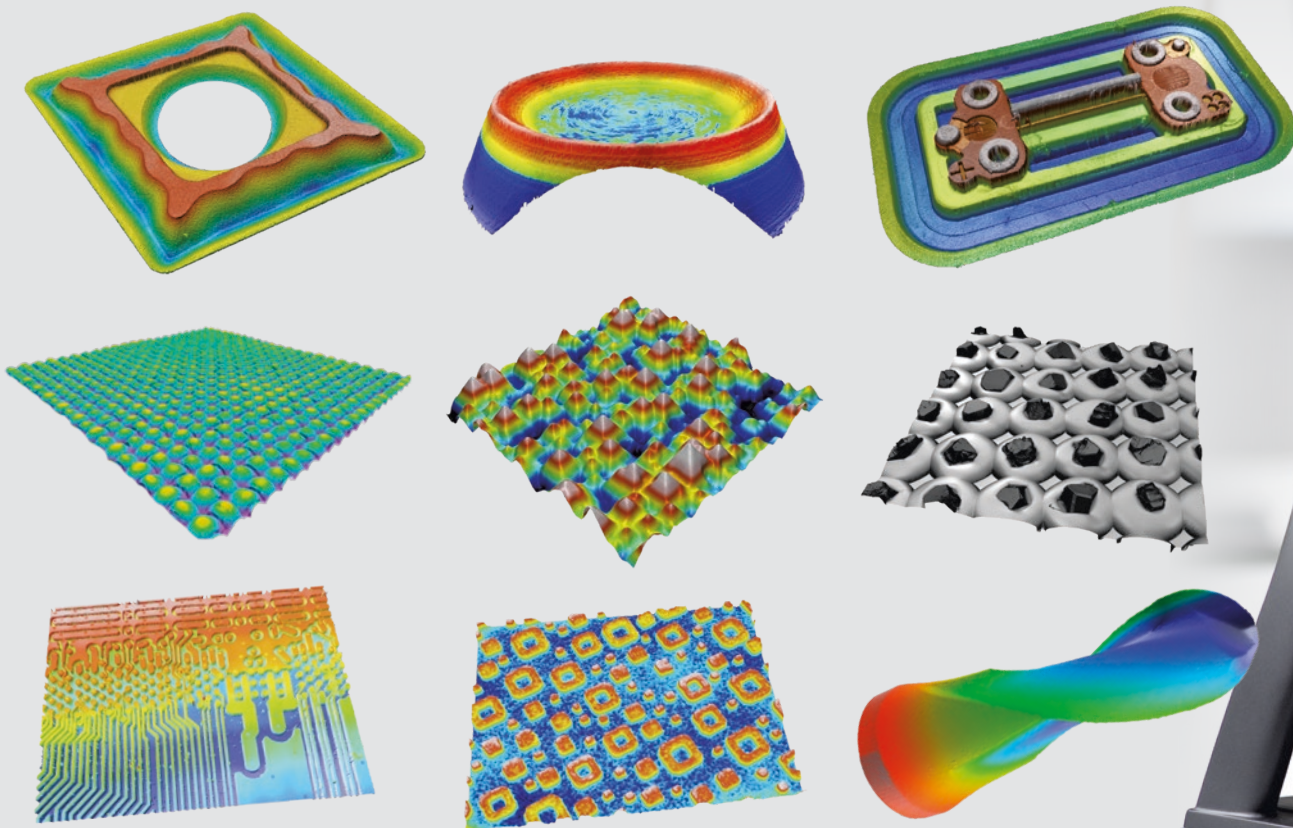
- Advanced manufacturing
- Aerospace & Automotive
- Archaeology & Paleontology
- Consumer electronics
- Defense & Security
- Medical devices
- Optics
- Tooling



# Versatile

## Quality control

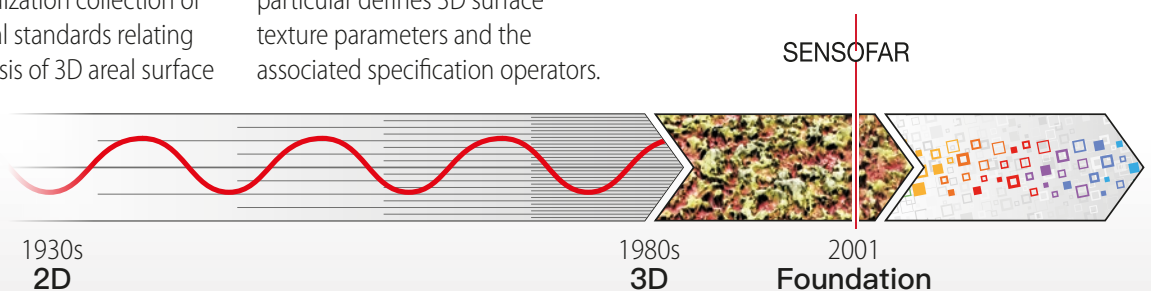
Automated modules have been created to facilitate all QC procedures. Ranging from operator access rights control, recipes, compatibility to barcode/QR readers, and customized plugins from our proprietary SensoPRO software to generate pass/fail reports. Our optimized solutions are able to work in QC environments due to their flexibility and easy-to-use interface, which can be programmed to work 24/7.



The ISO 25178: Geometric Product Specifications (GPS) – Surface texture: areal standard is an International Organization for Standardization collection of international standards relating to the analysis of 3D areal surface

texture. It is the first international standard taking into account the specification and measurement of 3D surface texture, and in particular defines 3D surface texture parameters and the associated specification operators.

## Surface texture characterization

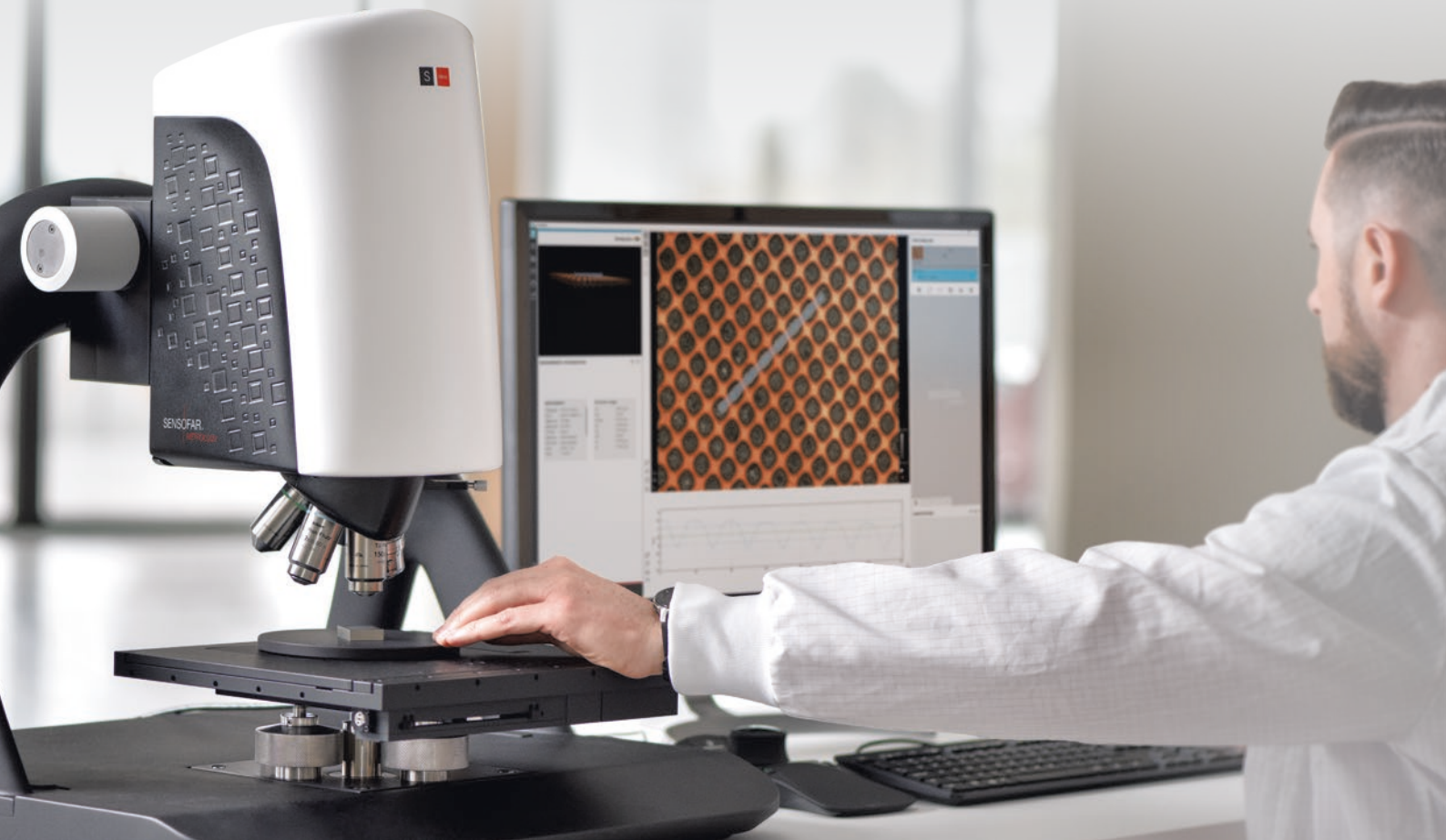




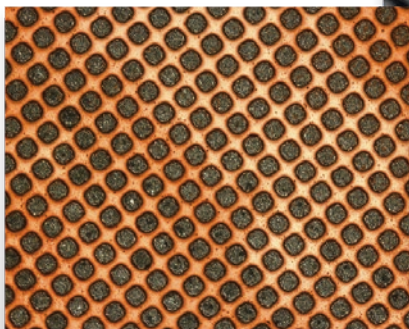
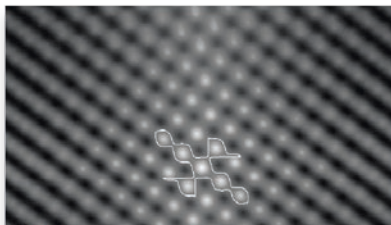
# system

## Research & Development

With Sensofar's 4-in-1 approach, a single click in SensoSCAN switches the system to the best technique for the task at hand. Each of the four measurement techniques found in the S neox sensor head -Confocal, Interferometry, Focus Variation, thin Film- contribute critically to the versatility of the system and help to minimize undesirable compromises in the data acquisition. The S neox is ideal for all lab environments, without limitations.



Surface parameters are calculated according to ISO 25178 and ISO 4287. Height, Spatial, Hybrid, Functional and Volumetric parameters are computed.



ISO 25178 / Height		ISO 25178 / Spatial	
Sa	2.5013 $\mu\text{m}$	Sai	7.6810 $\mu\text{m}$
Sku	2.1637	Sid	41.4000 $^\circ$
Smean	0.1321 $\mu\text{m}$	Str	0.1570
Sp	8.1049 $\mu\text{m}$		
Sq	2.9778 $\mu\text{m}$		
Ssk	0.2432	ISO 25178 / Hybrid	
Sv	6.3157 $\mu\text{m}$	Sdq	2.0758 $^\circ/\mu\text{m}$
Sz	14.421 $\mu\text{m}$	Sdr	135.8794 $^\circ$
ISO 25178 / Functional		ISO 25178 / Funct. Volume	
Sk	8.6025 $\mu\text{m}$	Vmc (...80%)	2.9430 $\mu\text{m}^3/\mu\text{m}^2$
Smc (10%)	4.2690 $\mu\text{m}$	Vmp (10%)	0.1006 $\mu\text{m}^3/\mu\text{m}^2$
Smr (...lane)	47.1301 $\%$	Vv (10%)	4.3543 $\mu\text{m}^3/\mu\text{m}^2$
Smr1	11.2838 $\%$	Vvc (...80%)	4.1375 $\mu\text{m}^3/\mu\text{m}^2$
Smr2	95.5967 $\%$	Vvv (10%)	0.2168 $\mu\text{m}^3/\mu\text{m}^2$
Spk	2.1054 $\mu\text{m}$		
Svk	1.0239 $\mu\text{m}$		
Sxp (...7.5%)	4.6290 $\mu\text{m}$		



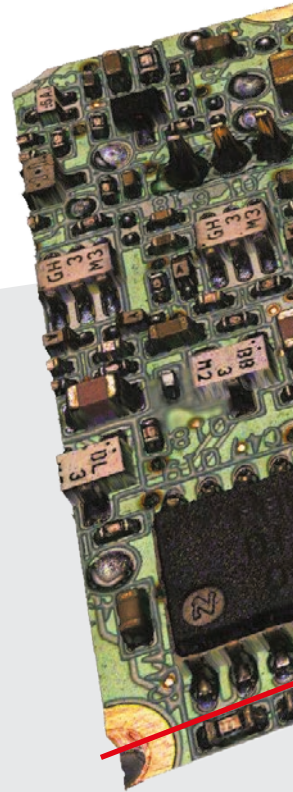
Since 2009, Sensofar has been member of the Technical Committee of the International organization for Standardization (ISO/TC213 WG16)

# Guided system

## SensoSCAN



Software drives the systems with its clear and intuitive user-friendly interface. The user is guided through the 3D environment, delivering a unique user experience.



### Sample Navigation

An overview tool helps the user to inspect the sample during measurement preparation, check measurement positions before acquisition as well as assist in the automation procedure. Working with high magnification will be easier, as you will know where you are at every moment.



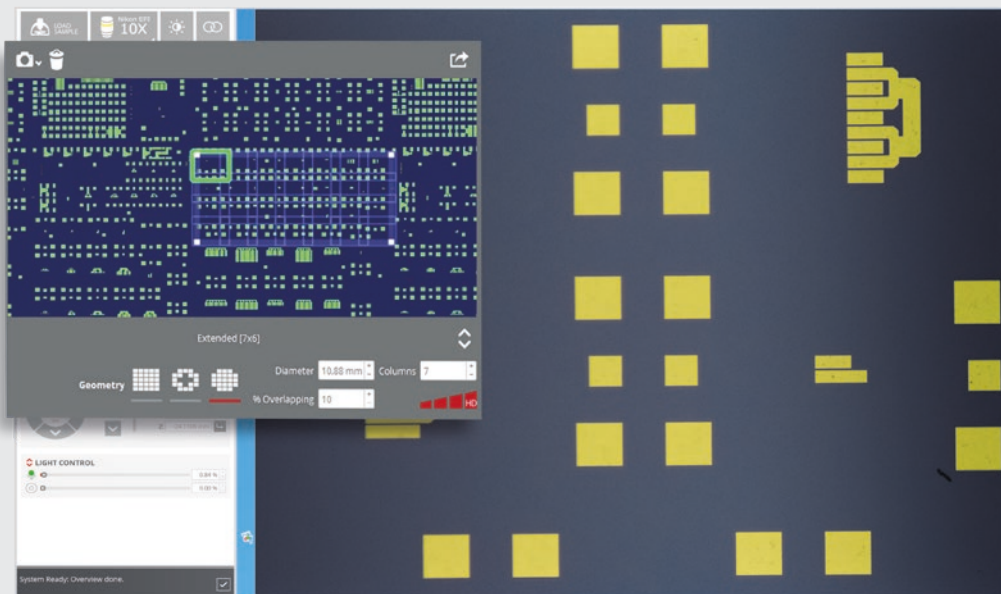
### Auto 3D Function

Selecting 3D Auto function, the SensoSCAN software automatically determines the correct illumination and the appropriate measurement range, and then performs the chosen measurement type. A high-quality result can thus be obtained within just a few seconds.

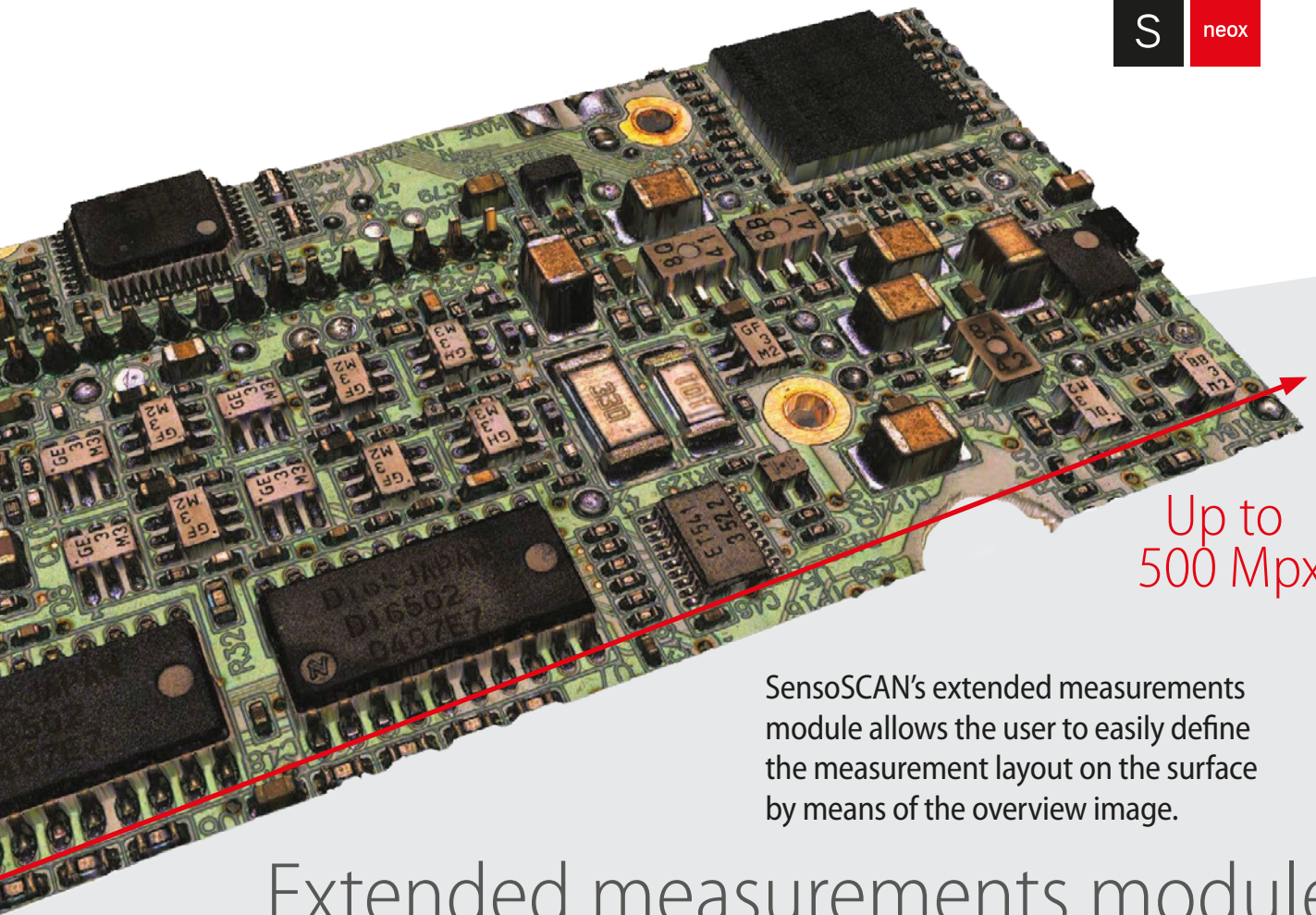


### Analysis & Reporting

It is also possible to create analysis templates to apply pre-determined filter and operator configurations to repeated measurements. And finally, obtain a clear and well-structured report for each measurement, showing the 3D data, a 2D profile and all the ISO parameters.







Up to  
500 Mpx

SensoSCAN's extended measurements module allows the user to easily define the measurement layout on the surface by means of the overview image.

## Extended measurements module

The area can be automatically cropped to rectangular, circular or ring areas of interest. Wide areas up to 500 million pixels are possible. Several scanning strategies such as autofocusing on each field, or focus tracking to minimize vertical scanning range are available.

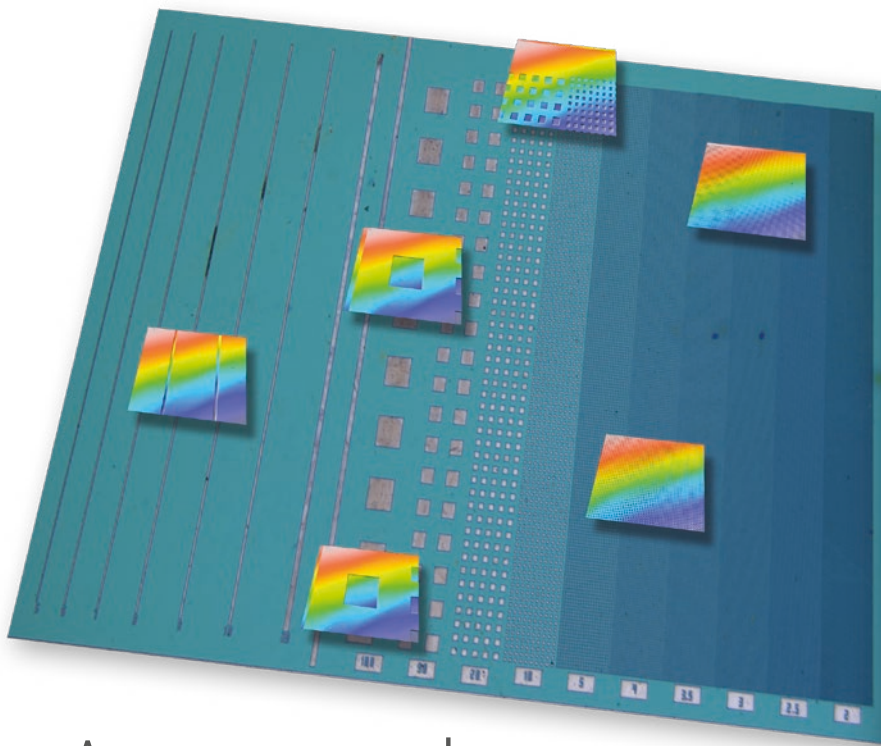


Sensofar is focused on providing customers with a user-friendly software experience. The redesigned UI and improved algorithms for the extended measurement module now give the user the versatility required for every surface, from ultra-smooth to rough surfaces. These changes greatly improve the results for height map and stack images.

### Multiple powerful acquisition settings

Numerous acquisition parameters can be adapted to best suit the intended measurement. For example, various autofocus settings help to reduce the acquisition time, the HDR function helps to improve the illumination of complex 3D structures and selectable Z-scan options also provide an opportunity to optimize the acquisition for varying 3D surfaces.





MMR | Wafer  
Name: 5 dia Cma.MMR  
Description:  
Total # measurements: 24

Positions						
#	X Abs.	Y Abs.	Z Abs.	Recipe Name	# Rep.	
1	0.0000	0.0000	----	Confocal Cma.smr	1	
2	1.0000	0.0000	----	Confocal Cma.smr	1	
3	2.0000	0.0000	----	Image Cma.smr	1	
4	2.0000	-1.0000	----	Confocal Cma.smr	1	
5	1.0000	-1.0000	----	Image Cma.smr	1	
6	1.0000	-2.0000	----	Confocal Cma.smr	1	
7	0.0000	-2.0000	----	Confocal Cma.smr	1	
8	-1.0000	-2.0000	----	VSI Cma.smr	1	
9	0.0000	-1.0000	----	Confocal Cma.smr	1	
10	-1.0000	-1.0000	----	Confocal Cma.smr	1	
11	-2.0000	-1.0000	----	Confocal Cma.smr	1	
12	-2.0000	0.0000	----	Confocal Cma.smr	1	
13	-2.0000	1.0000	----	Confocal Cma.smr	1	

**Movement settings**

Retract to Absolute Z position

Use Objective: Nikon - EPI 20X

Use references

# Ref. 2 Graf. 0 Circle Diameter 1.00 mm

Select object: Nikon - EPI SX

X Rel. Y Rel. Z Rel.

Ref. 1 -24.9200 17.0306 -10.5147

Ref. 2 -24.9200 17.0306 -10.5147

**Repeatability**

Time between measurements: 1 s

Dynamic test

**Time delay**

Time delay before 1st measurement: 0.00 min

**Results**

Root folder: c:\tmp

Group by: SingleAcquisition

Base Name: 5 dia Cma

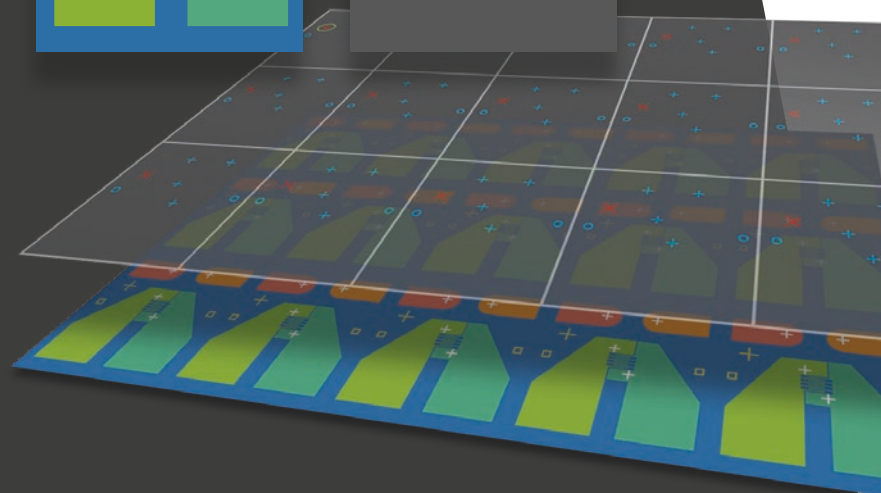
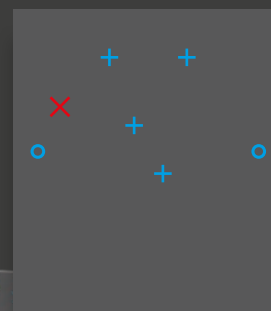
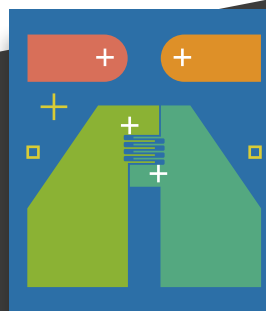
Average All  Average in same position

# Automated procedures module

The automated procedures module is an easily customizable tool for creating quality control procedures. Creating and running multiple measurement recipes is accomplished using our recipe tool that commands the system to perform several measurements at pre-defined positions. The module combined with tools such as the user manager, sample identification, data exportation, and 'pass or fail' tolerance comparison provides all what is need for QC inspection.

## Ready for arrays of samples

The S neox introduces a new functionality that allows to replicate a defined multiple measurement recipe to an array of samples. The multiple measurements will thus be repeated at each sample relative to each sample's reference point. This simplifies the programming of these recipes, as the recipe is defined only once, and improves the reliability. This will solve long-standing requirements from customers working in QC 24/7.



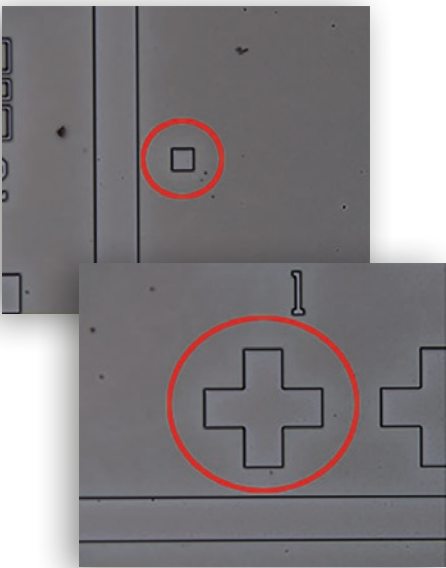
# System validation package

Every S neox is manufactured to deliver accurate and traceable measurements. Systems are calibrated using traceable standards following the ISO 25178 standard part 700 and part 600 for: Z amplification factor, XY lateral dimensions, flatness deviation, system noise as well as parcentricity and parfocality. Any metrology instrument must fulfill it before providing any result.



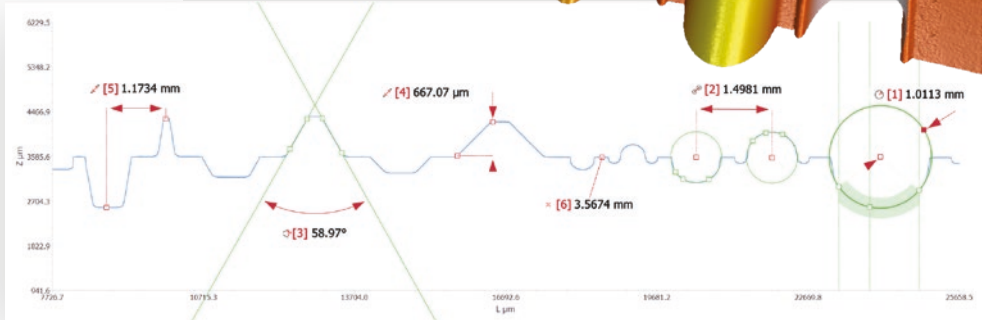
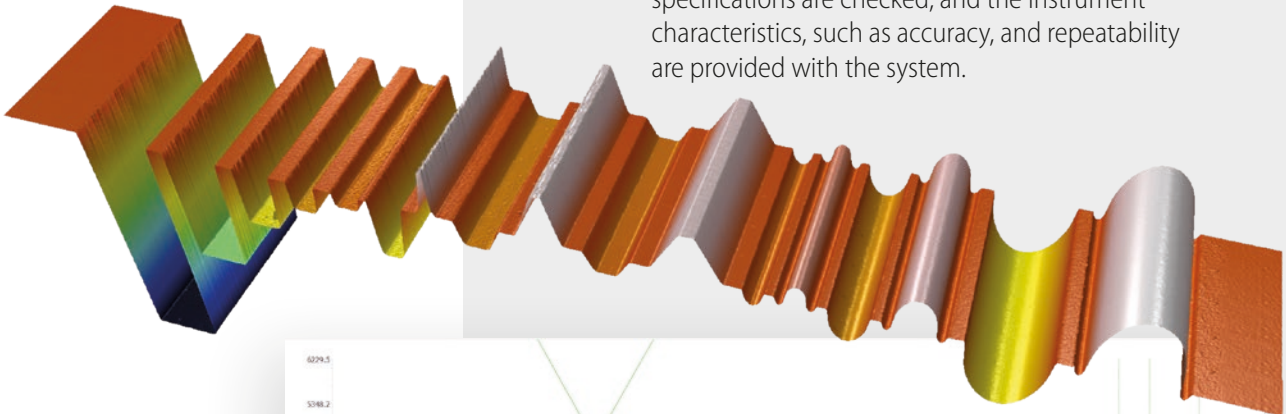
Sensofar systems are in accordance to ISO 25178 standard, providing a truly reliable instrument for surface characterization.

Every S neox is **calibrated** to estimate the metrological characteristics using a traceable calibration standard, **adjusted** to correct systematic errors and **verified** to match the calibrated value. Finally, the **performance** specifications are checked, and the instrument characteristics, such as accuracy, and repeatability are provided with the system.



## Automatic reference recognition

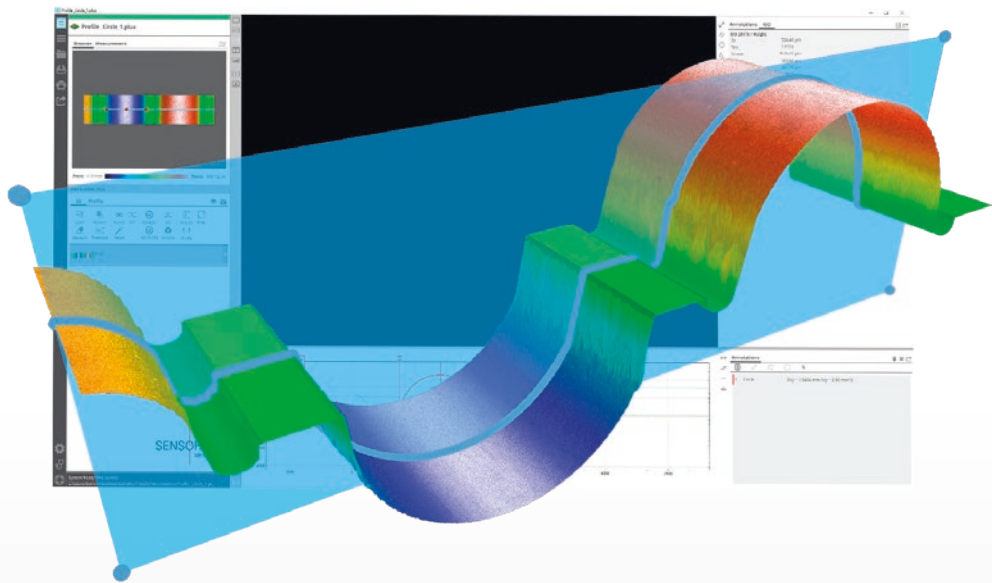
The S neox now includes automatic detection of fiducials, based on pattern matching algorithms, that enables fully-automated operation without human interaction. What used to be difficult and imprecise, now becomes easy, repetitive, and accurate. The combination of this reference recognition and our automated routines is a step-forward towards industry 4.0.



# SensoVIEW

# Powerful analysis software

SensoVIEW is an ideal software for a broad range of analysis tasks. It includes a comprehensive suite of tools for preliminary examination and analysis of 3D or 2D measurements, allowing roughness or volume calculations and measuring critical dimensions (angles, distances, diameters) with a set of analysis tools.



Five smart visualization modes (false color, stack, stack & false color, true color or directional luminance) are always within reach in the main screen.

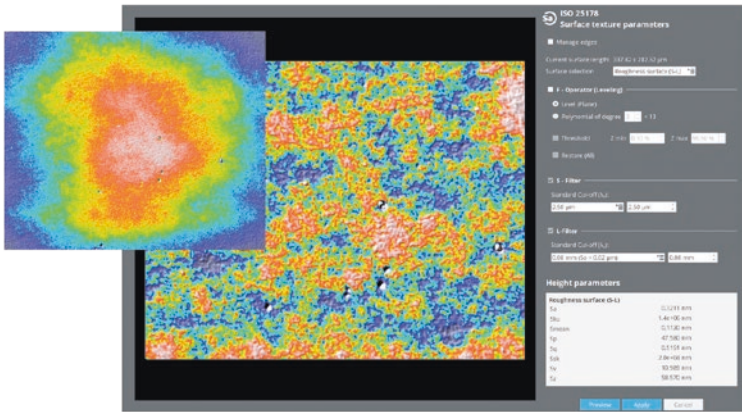
## The most perceptive visualization of your topographies

Image control options are always in continuous development for an excellent fit to all sample types and customer needs. A full range of image processing settings are included in each of the rendering visualizations choices and presented together with scale options for a better adjustment.



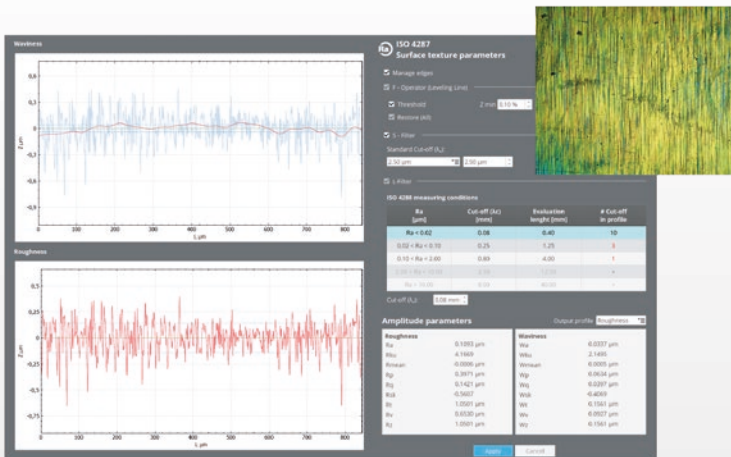
# Smart calculations tool for key parameters

SensoVIEW provides a specific step-guide to get surface texture parameters according to ISO 4287 and 25178 with just one click.



## ISO 25178 calculations

Designed for users without a deep knowledge of ISO filters, who can now extract this information, by simply selecting the type of surface being analyzed. This operator filters the surface according to ISO 25178, returning the surface texture parameters.



## ISO 4287 calculations

It automatically filters the primary profile according to ISO 4287 and ISO 4288, returning the roughness (Rx) and waviness (Wx) parameters. The calculation of the parameters consists of a set of predefined operators, filters (F-Operator, S-Filter and L- Filter) and additional settings.

# Simple yet powerful, designed for you

This dynamic software provided with the system offers a complete set of user friendly tools for displaying and analyzing measurements. The user is trained and guided through the 3D environment, delivering a unique user experience: Access to operators in just one-click; icons with eye-catching design; a better function understanding; and simultaneous 3D, 2D and profile views are just some of the key features of the SensoVIEW software.



## Choose your own view

3D and 2D interactive views provide multiple scaling, display and render options.



## Process your data

Full set of operators to process the data information or generate alternative layers.



## Interact with analysis tools

Broad range of analysis tools for preliminary examination and analysis of 3D or 2D measurements.



## Get your results

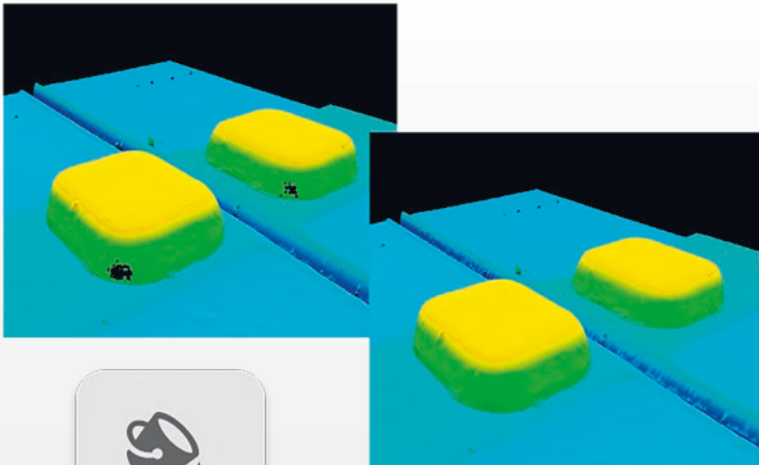
Get a customizable report or export the 3D measurement data in multiple formats.

# Guided measurement



## Sequential operators

A smart suite of operators, which can be applied to 3D/2D measurements and profiles, provides the opportunity to remove form, apply a threshold, retouch data points, restore non-measurable data and apply a range of filters and/or generate alternative layers by cropping, subtracting or extracting a profile.



### Restore

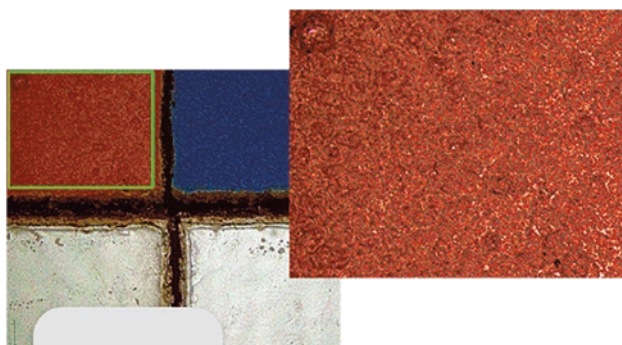
The Restore operator is used to fill (replace) non-measured data points with Z values. This is done either by using adjacent 'good' data to interpolate a replacement value, or by simply replacing all non-measured points with a fixed value. The user can choose between restoring the complete area or filling only zones with less than a certain number of points.



### Rescale

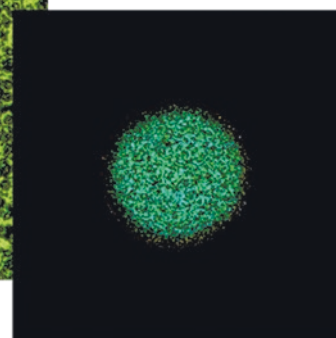
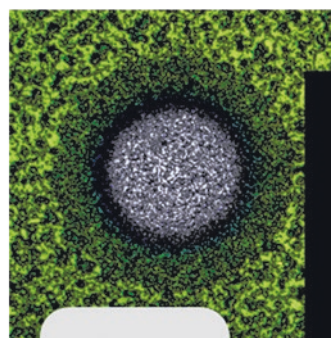
This applies a user-defined vertical factor and vertical offset to the data. It is an ideal operator to create an inverted 3D of your sample, for measuring replicas.

# examination



## Crop

New areas can be extracted from a raw measurement or from an 'operated' measurement to select the region of interest from your sample.



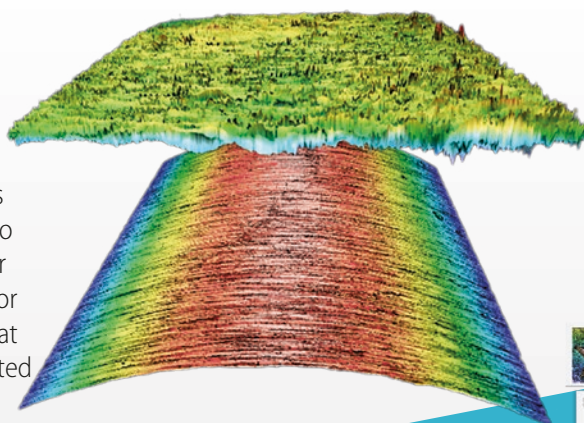
## Threshold

Useful for filtering the data by adjusting sliders on a histogram. Z values outside the slider's limits are set to non-measured points.



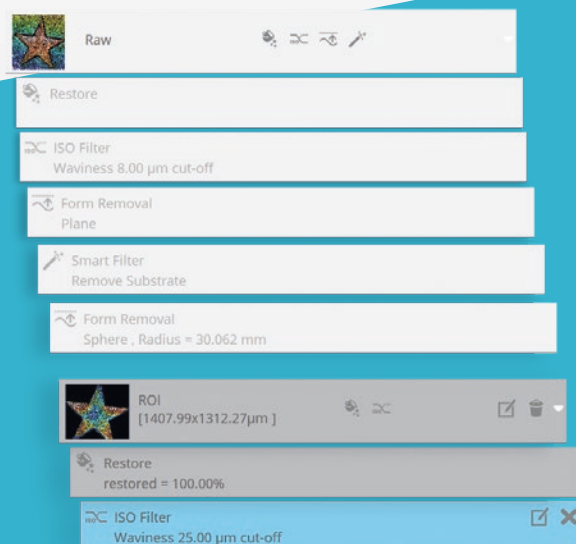
## Form removal

The form removal operator is used for samples that need to be leveled due to a tilt (linear form), an inherent spherical or cylindrical component, or that exhibit or possess an unwanted polynomial term.



## Doing repetitive tasks, efficiently

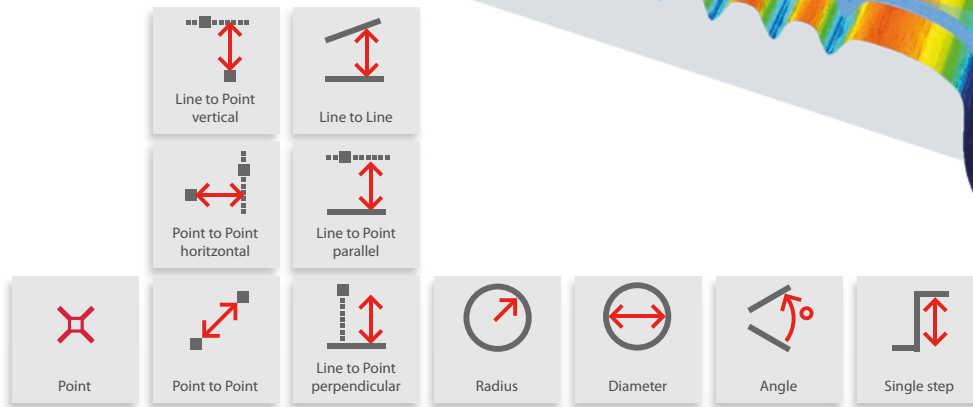
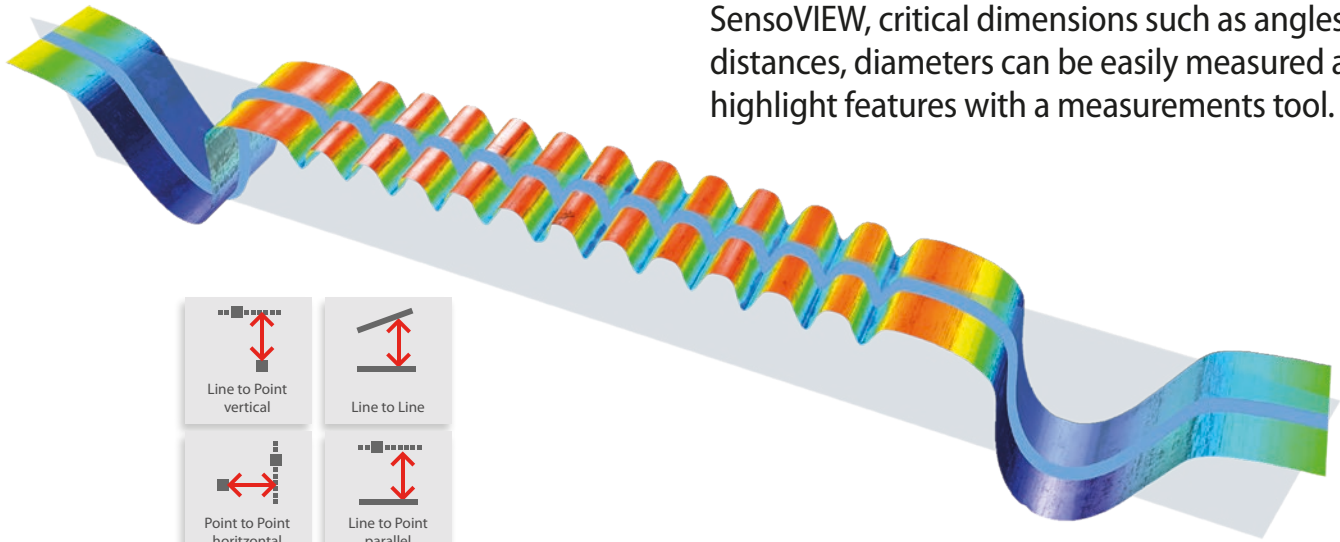
When a process data analysis is defined, it is possible to create analysis templates to apply these pre-determined filters and operator configurations to repetitive measurements.



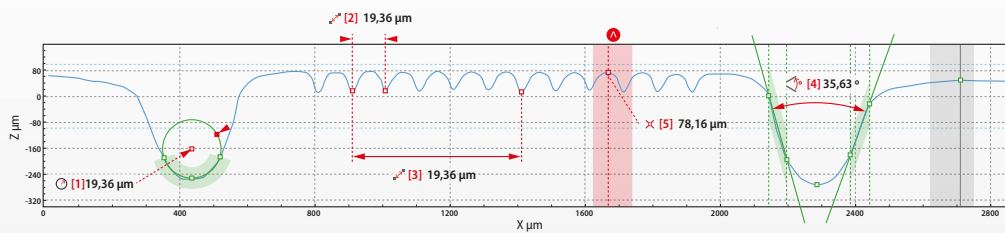


# Measuring critical

Always with the priority of facilitating operations and procedures for the user, assist tools have been developed for critical dimension options. With SensoVIEW, critical dimensions such as angles, distances, diameters can be easily measured and highlight features with a measurements tool.



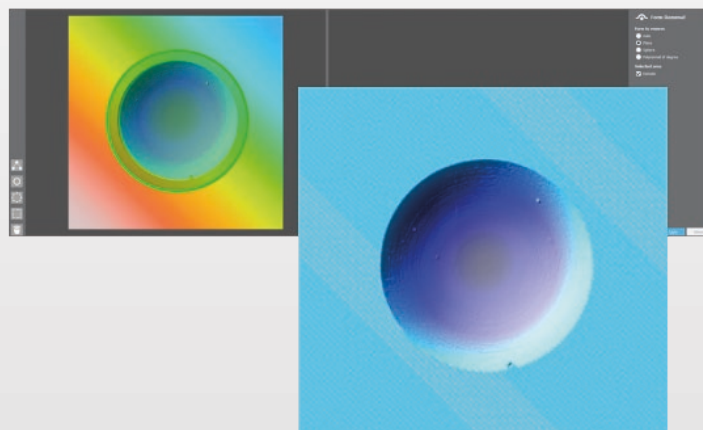
## Multiple measurement tools



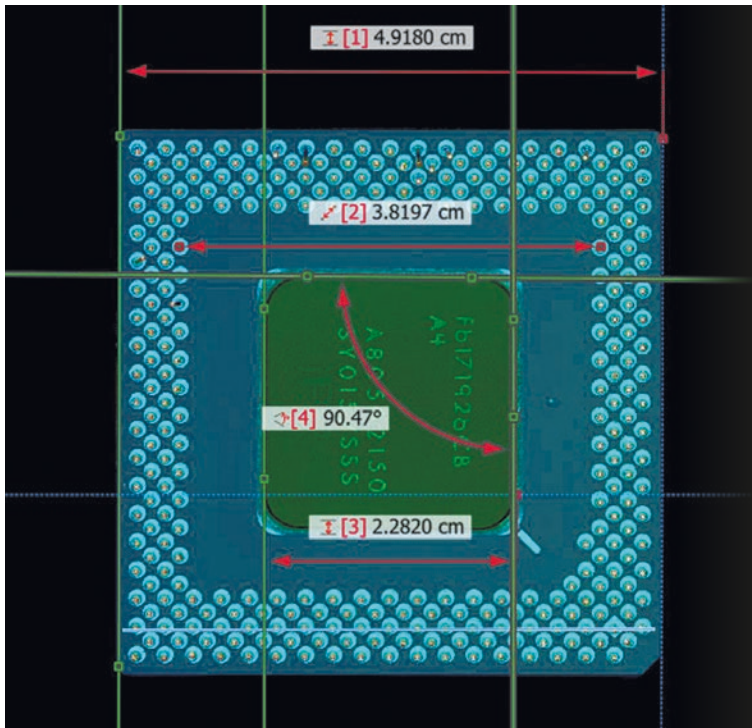
A complete assortment of tools ready to add the most essential dimensions when measuring (radiuses, angles, diameters, step heights and perpendicular & parallel distances). These tools will return a numerical value for a particular dimension.

## Volume geometries

Volume calculation allows the user to get the volume of a 3D topography region. Two modes are possible: thresholding (defining the minimum and maximum Z limits) or leveling (defining a ROI by circle, polygonal or rectangular geometries).



# dimensions in all axes



## Useful assist measurement tools

Assist tools are a quick and handy way to draw the most basic and primary forms (points, lines and circles) in selected rendering views to, later on, add the corresponding dimensions. It is an optional aid when drawing the measurement tools.



↓ 1	↕ Parallel	4.9180 cm	×
↓ 2	↗ Two points	3.8197 cm	×
↓ 3	↕ Parallel	2.2820 cm	×
4	↻ Angle	90.47°	×



## Customizable reports

With the possibility to choose from different report templates, the user can configure every section to fit as much as possible to their requirements. A flexible way to obtain clear and well-structured reports for each measurement, showing the acquisition information, 3D data, a 2D profile and all the ISO parameters, among others.

## SensoMAP



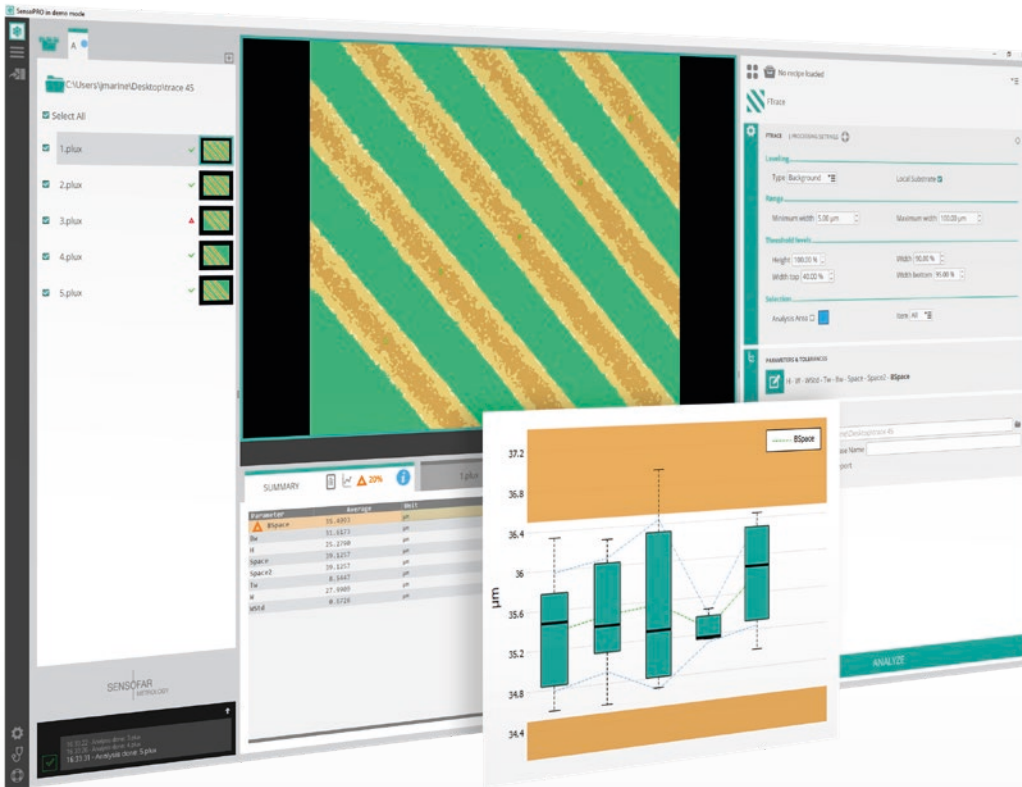
SensoMAP, based on Mountains technology from Digital Surf, is an extremely powerful tool for analysis and reporting. SensoMAP software is completely modularly adaptable to customer requirements. Two levels (standard and premium) and several modules (2D, 3D or 4D modules, Advanced Contour, Grains & Particles, Statistics and Stitching) are available.

# SensoPRO

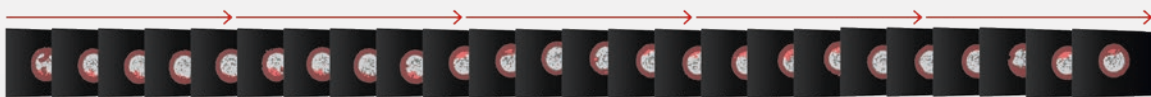


24/7

# Rapid Quality Control



It has never been so easy to perform fast quality control in a production line. Thanks to SensoPRO, the operator in the production line only needs to load the sample and follow guided instructions. Plug-in-based data analysis algorithms provide a high degree of flexibility.



Latest version



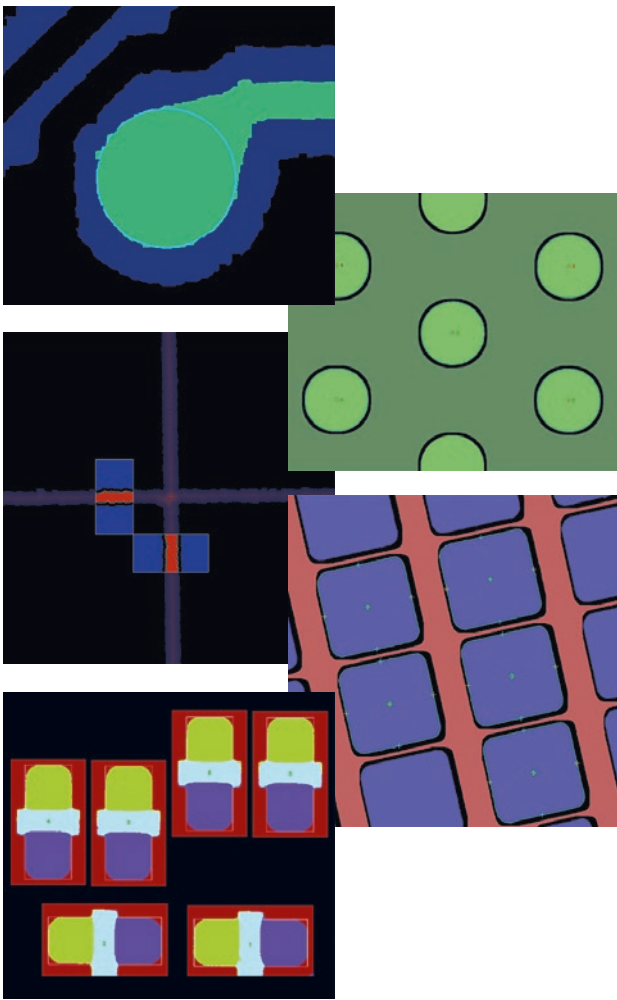
Previous version

X5  
faster

## Extremely fast

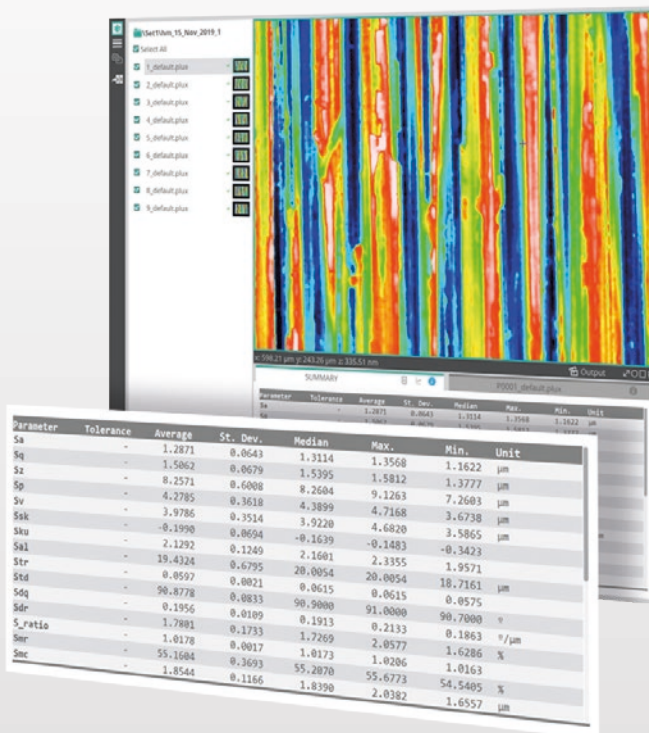
As multiple cores can now be fully utilized, a larger number of actions can be implemented in parallel, thus resulting in higher overall system performance. Easy to handle larger files, and/or larger multiple data sets.





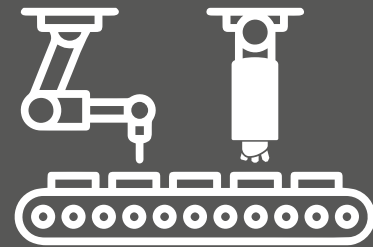
## Results

Once the analysis is done, the results and the standard deviations for each parameter are shown on a table. If any tolerances are applied, these will be highlighted in the summary section. A part from that, the data visualization is also discretized, it is reduced to the physical aspects for that feature fitted by the analysis. When multiple features are detected, they are numbered and can be selected to reveal the individual fit parameters.



## How does it work?

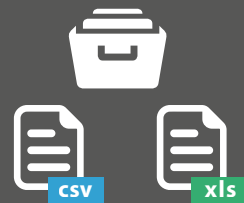
This 64-bit data analysis solution provides an environment for QA engineers and technicians to quickly and easily analyze production parameters. Sensopro can be linked to the acquisition software (SensoproSCAN) so that measured data can be automatically transferred to Sensopro and analyzed. Once configured, a single-click both acquires and analyzes the measurement data.



ACQUISITION & DATA PROCESSING



SENSOPRO TOLERANCE ANALYSIS



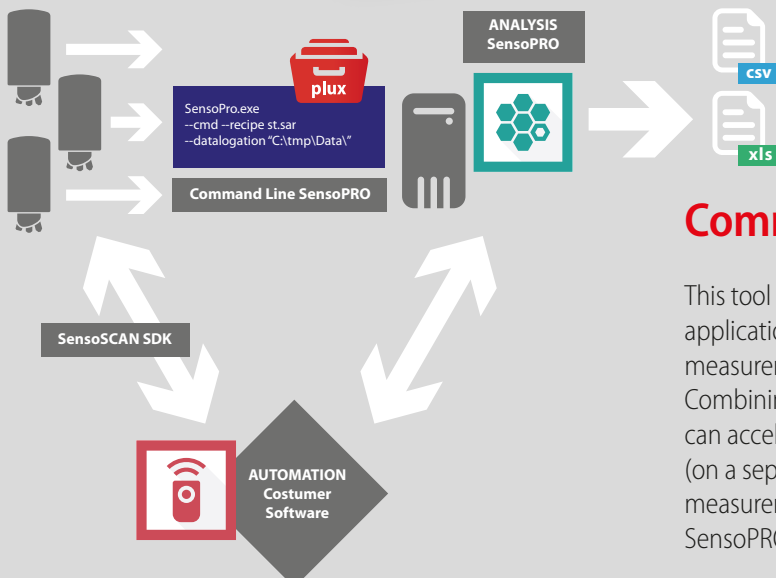
EXPORT RESULTS IN DIFFERENT FORMATS

Several options for managing the output files from a successful analysis are provided to get a complete report showing pass or fail results.

# Guide tool for the QC manager



A revolutionary innovation for optical profilometers which substantially improves its usability and simplifies the task of setting tolerances when creating a recipe, as well as deciding which are the key parameters to control the production line by comparing multiple sets of data. Specially conceived for non-expert users who need traceable production control.



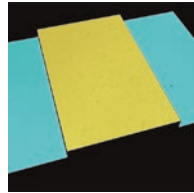
## Command line available

This tool is a solution to create proprietary applications able to manage Sensopro to analyze measurement acquired with Sensofar systems. Combining this solution with Sensopro SDK, we can accelerate QC processes by analyzing in parallel (on a separate computer) while acquiring new measurements. Command line is an easy way to call Sensopro analysis software from other software.

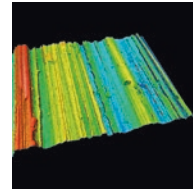
## Default Plugins



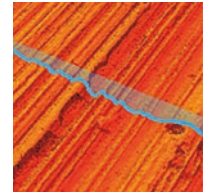
Step Height



Step Height ISO

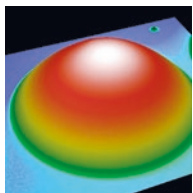


Surface Texture

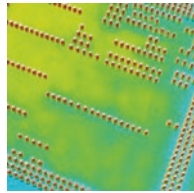


Surface Texture Profile

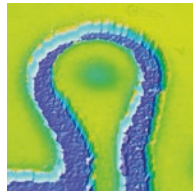
## Optional Plugins



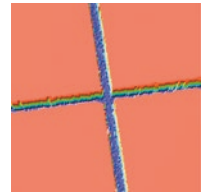
Aspheric



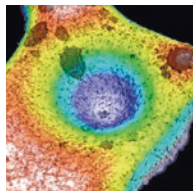
Bump



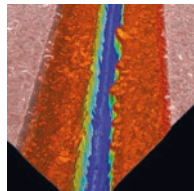
Circle Pad



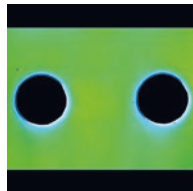
Cross Kerf



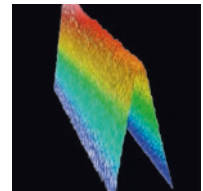
Dimple



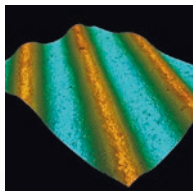
Double SH



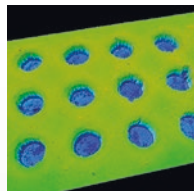
Dual Hole



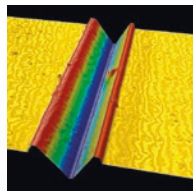
Edge



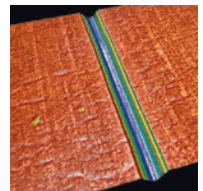
Ftrace



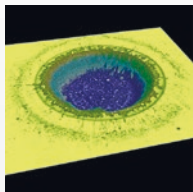
Hole



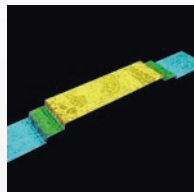
Laser Cut



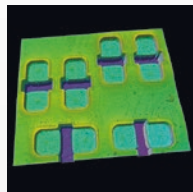
Laser Groove



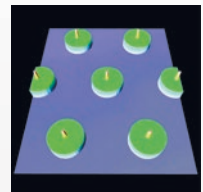
Laser Hole



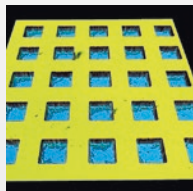
Multiple SH



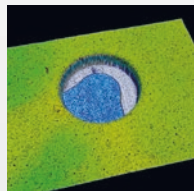
Pad



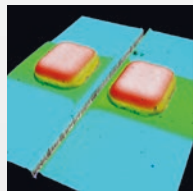
Pillar



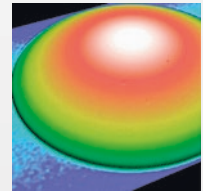
R Hole



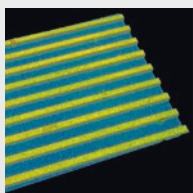
Solder Mask



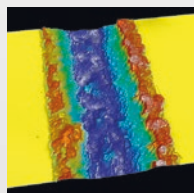
Spacer



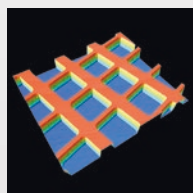
Spheric



Trace



Trench



Wafer Pad

## SensoPRO Plugins

This Plugin-based data analysis approach also provides a high degree of flexibility and specificity, making use of targeted algorithms that are optimized to the exact application needs.

### Processing settings

Comprising threshold settings, filters, operators, crop settings, etc., that can be applied to the measured data before the analysis. Each Plugin has its own suite of processing settings.

### Parameters & Tolerances

Set of fitting parameters and selection of tolerances for further analyses. Optimizes the results, e.g. according to known results, scaling, (manufacturing) conditions and tolerances.

Parameter	Average	St. Dev.	Unit
L1	182.965	1.26832	µm
W1	186.62	0.666153	µm
Z1	16.3865	0.195507	µm
Z2	15.8412	0.2756	µm
Z01	9.23902	0.539519	µm
Z02	9.78429	0.621179	µm
L2	192.425	2.06669	µm
W2	186.62	1.05328	µm
SL	455.8	1.94215	µm
SW	189.2	1.05328	µm
D	89.655	1.57992	µm
D1	1.29	1.15381	µm
D2	1.29	2.15858	µm
D3	0.86	1.33231	µm
D4	1.72	1.33231	µm

## Customized Plugins

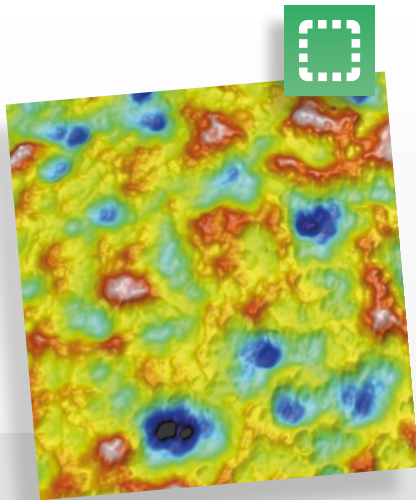
Sensofar adapts and develops all the analysis solutions you may need for your specific application.



# Why 4-in-1 tech

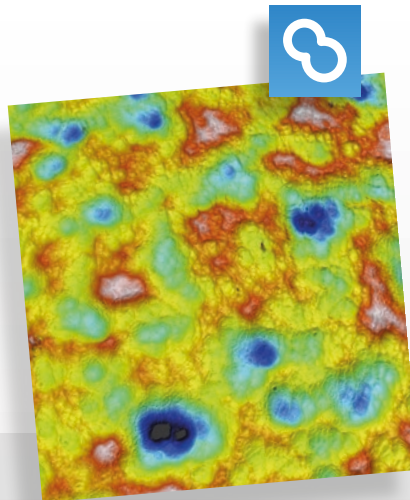
## Ai Focus Variation

**Active illumination Focus Variation** is an optical technology that has been developed for measuring the shape of large rough surfaces. This technology is based on Sensofar's extensive expertise in the field of combined confocal and interferometric 3D measurements, and is specifically designed to complement confocal measurements at low magnification. It has been improved with the use of active illumination to get more reliable focus location even on optically smooth surfaces. Highlights of the technology include high slope surfaces (up to 86°), highest speed (up to 3mm/s) and large vertical range measurements.



## Confocal

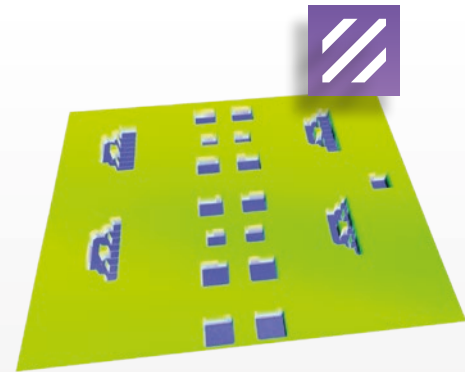
**Confocal** profilers have been developed to measure the surface height of smooth to very rough surfaces. Confocal profiling provides the highest lateral resolution, up to 0.15  $\mu\text{m}$  line & space, with spatial sampling can be reduced to 0.01  $\mu\text{m}$ , which is ideal for critical dimension measurements. High NA (0.95) and high magnification (150X) objectives are available to measure smooth surfaces with steep local slopes over 70° (for rough surfaces up to 86°). The proprietary confocal algorithms provide vertical repeatability on the nanometer scale.



## Interferometry

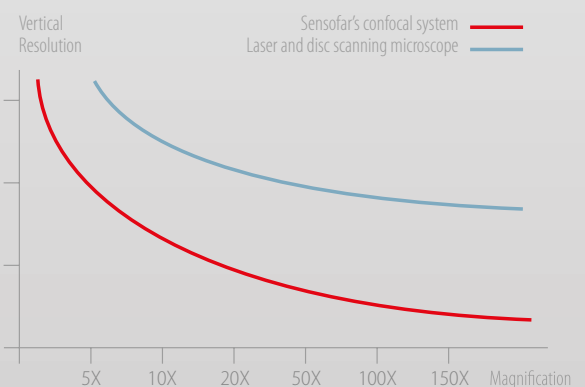
**PSI** Phase Shift Interferometry has been developed to measure the surface height of very smooth and continuous surfaces with sub-Angstrom resolution, for all numerical apertures (NA). Very low magnifications (2.5X) can be employed to measure large fields of view with the same height resolution.

**CSI** Coherence Scanning Interferometry uses white light to scan the surface height of smooth to moderately rough surfaces, achieving 1 nm height resolution at any magnification.



## No moving parts

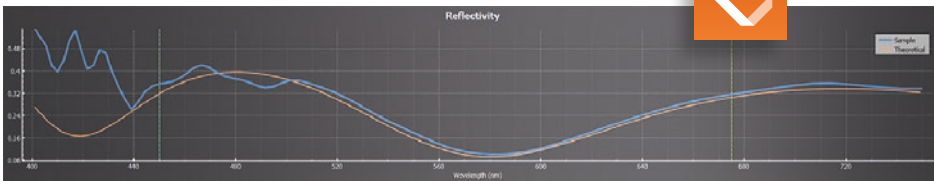
The confocal scanning technique implemented in Sensofar's systems is a Microdisplay Scan Confocal Microscope (ISO 25178-607). The microdisplay creates a rapidly switching device with no moving parts, making data acquisition fast, reliable and accurate. Due to this and the associated algorithms, Sensofar's confocal technique yields a class-leading vertical resolution, better than other confocal approaches and even better than laser scanning confocal systems.



# nologies?

## Thin film

**Thin film** measurement technique measures the thickness of optically transparent layers quickly, accurately, non-destructively and requires no sample preparation. The system acquires the reflectance spectrum of the sample in the visible range, and is compared with a simulated spectra calculated by the software, with layer thickness modification until the best fit is found. Transparent films from 50 nm to 1.5 μm can be measured in less than one second. Sample evaluation spot diameter is dependent on the objective magnification which can be as low as 0.5 μm and up to 40 μm.



AI FOCUS VARIATION	CONFOCAL	INTERFEROMETRY

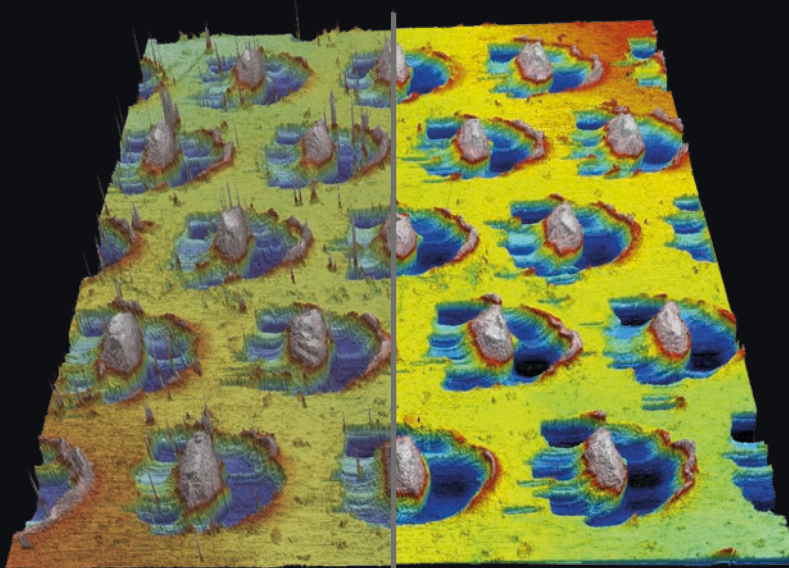
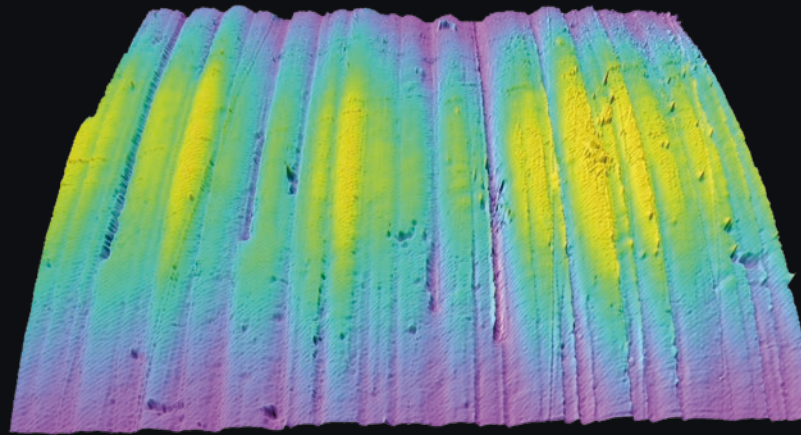
	AI FOCUS VARIATION	CONFOCAL	INTERFEROMETRY
Rough samples	★ ★ ★	★ ★ ★	★
Smooth samples	★	★ ★	★ ★ ★
Micro-scale features	★ ★	★ ★ ★	★ ★ ★
Nano-scale features		★ ★	★ ★ ★
High local slopes	★ ★ ★	★ ★	★
Thickness		★ ★ ★	★ ★ ★



# Features that make the

## Continuous Confocal

Revolutionary step in Confocal measurement technology, steadily reducing the acquisition time by a factor of 3. Continuous Confocal mode avoids the discrete (and time-consuming) plane-by-plane acquisition of classical Confocal by simultaneously scanning the in-plane and Z axis. Essential for reducing acquisition times for large area scans and large Z scans.



Applying SND

## Smart noise detection

S neox uses a detection algorithm (SND) to detect those pixels in which the data is not reliable. In comparison to other techniques that use spatial averaging, S neox does this process pixel by pixel without compromising lateral resolution.

## HDR

High Dynamic Range mitigates reflection and drop-out points on highly reflective surfaces.

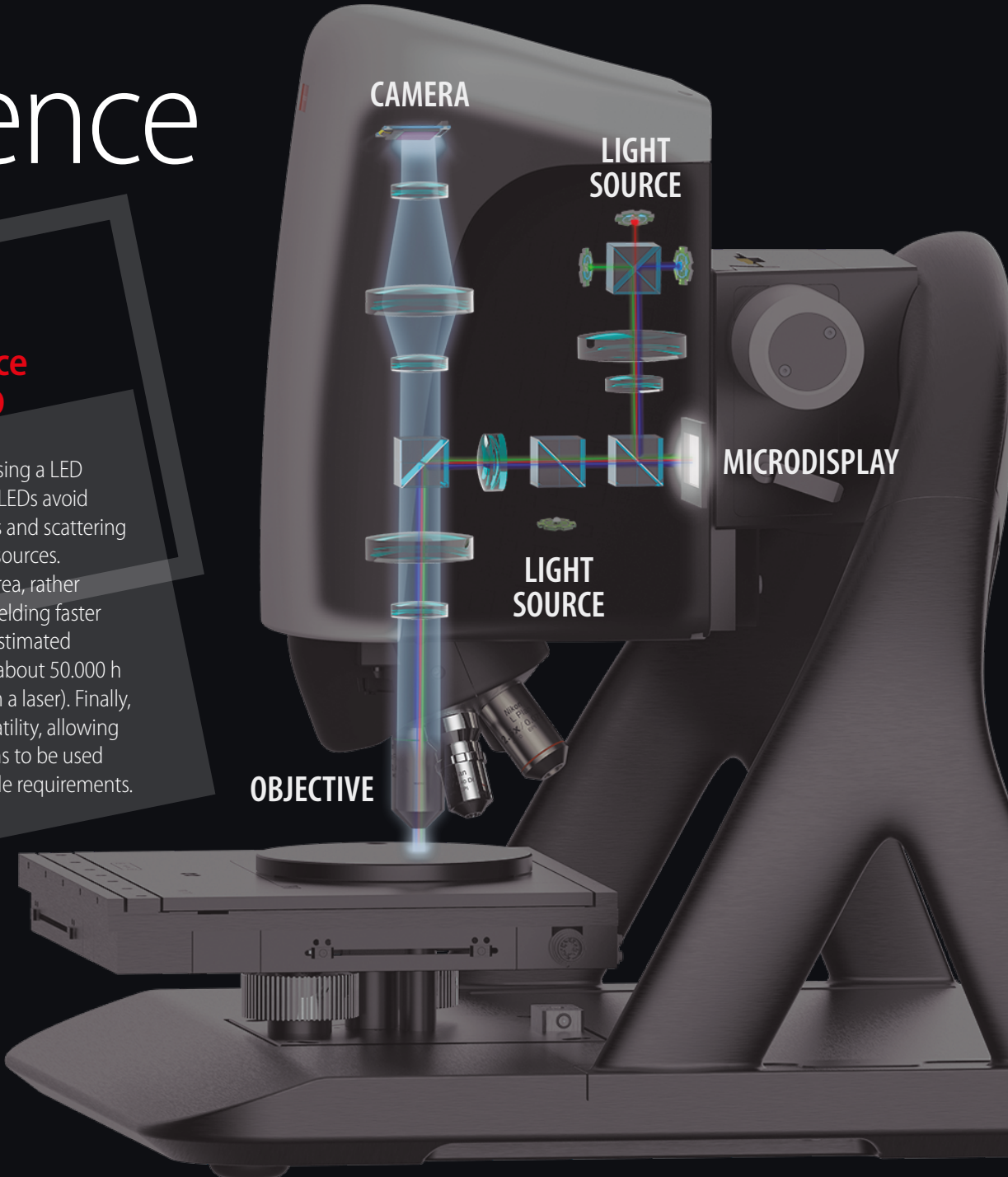




# difference

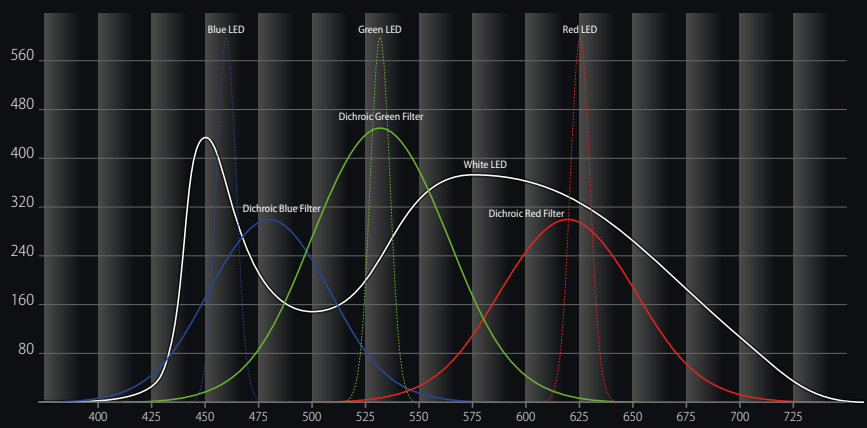
## Improving performance using a LED

The advantages of using a LED over a laser are vast. LEDs avoid interference patterns and scattering typical of laser light sources. LEDs illuminate an area, rather than a single spot, yielding faster measurement. The estimated lifetime of an LED is about 50.000 h (25 times better than a laser). Finally, they offer great versatility, allowing different wavelengths to be used depending on sample requirements.

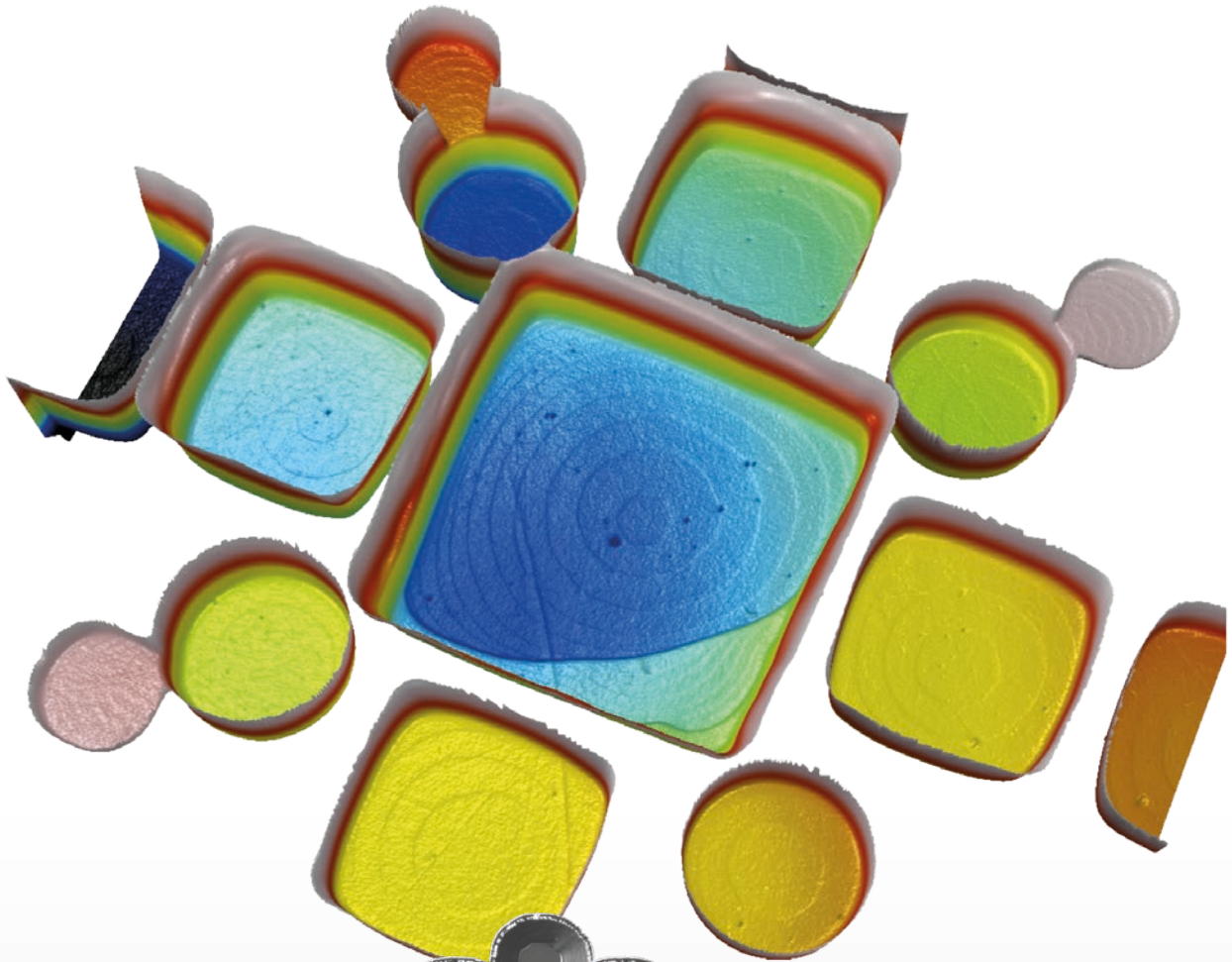


## Multispectral wavelength LEDs

Focused on optimizing the light source for each application, S neox has four LED light sources inside its optical core: red (630 nm), green (530 nm), blue (460 nm) and white. Shorter wavelength is used on those applications where the highest lateral resolution is required. Longer wavelengths provide greater optical coherence, up to 20 μm, making Phase Shifting Interferometry possible on large area smooth surfaces. Additionally, the red, green and blue LEDs are pulsed to acquire real color images and high contrast color-coded depth information in real time.



# Outstanding lateral &



## DIC observation

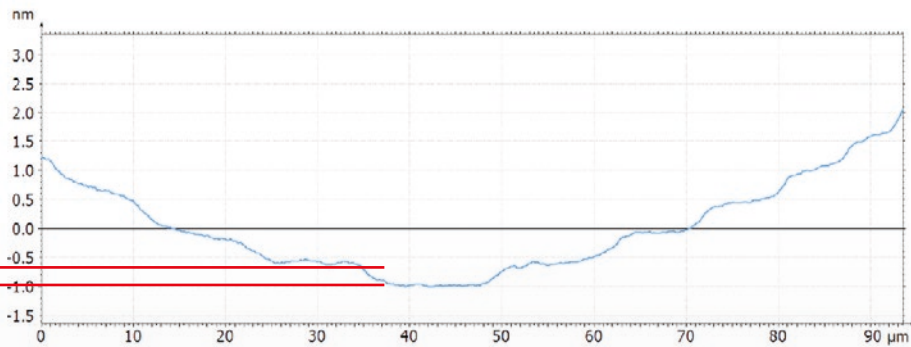
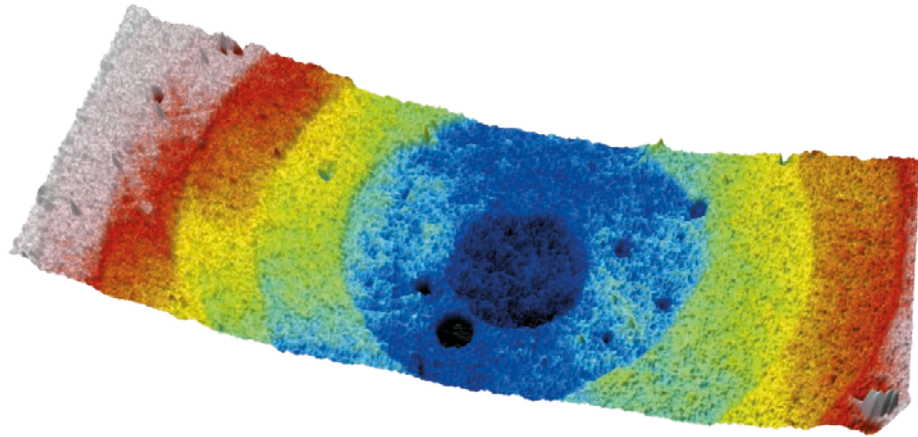
Differential Interference Contrast (DIC) is used to emphasize very small height features that have no contrast in normal observation. With the use of a Nomarski prism, an interferential image is created resolving sub-nanometer scale structures not visible in brightfield or confocal images.



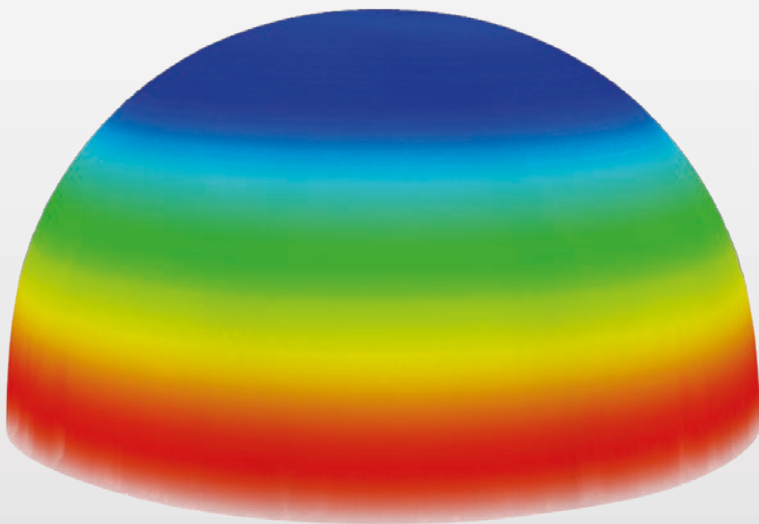
# vertical resolution

## High resolution

Vertical resolution is limited by the instrument noise, which is fixed for Interferometry, but dependent of the numerical aperture for Confocal. Sensofar proprietary algorithms deliver nanometer level system noise for any measurements technique at the highest possible lateral resolution for an optical instrument. The topography shown is a sub-nanometer (0.3 nm) atomic layer. Courtesy of PTB.



0.3 nm  
Step height



## High slopes

Numerical Aperture (NA) of the microscope objective limits the maximum measurable slope on optically smooth surfaces, while optically rough, or scattering surfaces, provide signal beyond that limit. Sensofar algorithms are designed to measure up to  $71^\circ$  on smooth surfaces (0.95 NA), and up to  $86^\circ$  on rough samples.



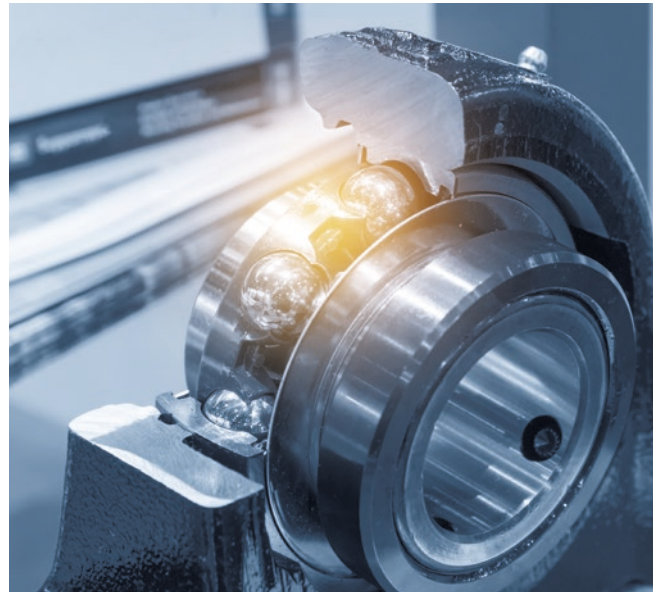
# USER'S EXPERIENCE

“ The new S neox is beautifully engineered to make it an outstanding instrument for measuring surface textures

It is amazingly fast and has excellent resolution. The flexibility and combination of Confocal, Interferometry, and Ai Focus Variation, along with excellent analysis options, make it a fantastic tool for a wide range of research and studies, covering many applications, topographies, and materials. ”



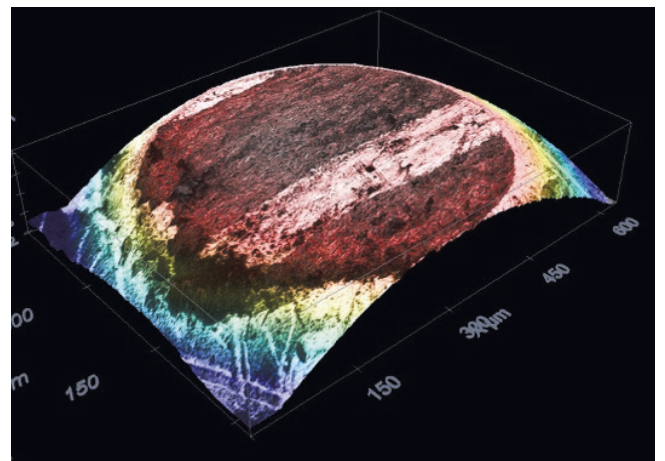
Prof. Christopher A. Brown  
Ph.D., PE, FASME  
Director, Surface Metrology Lab  
Department of Mech I Engineering  
Worcester Polytechnic Institute, USA



## TRIBOLOGY

### Transfer layer evolution during friction in W-C:H coatings

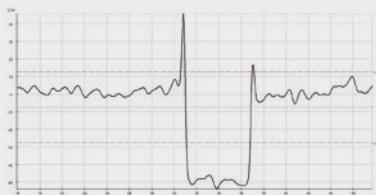
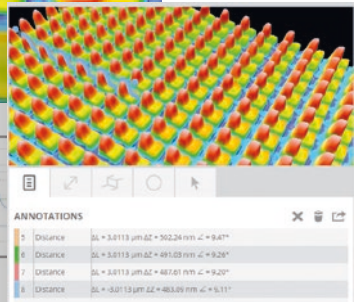
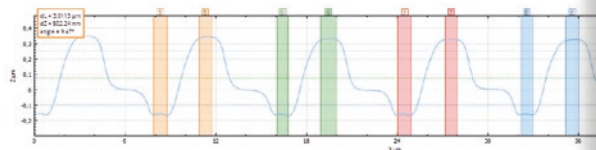
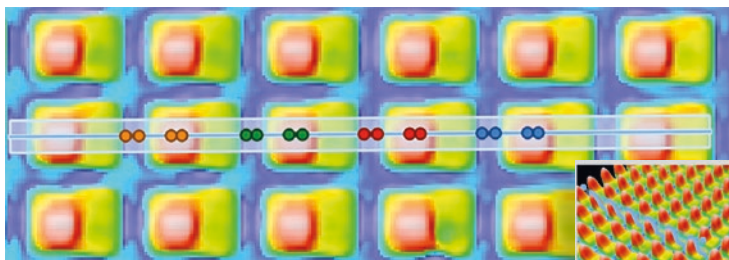
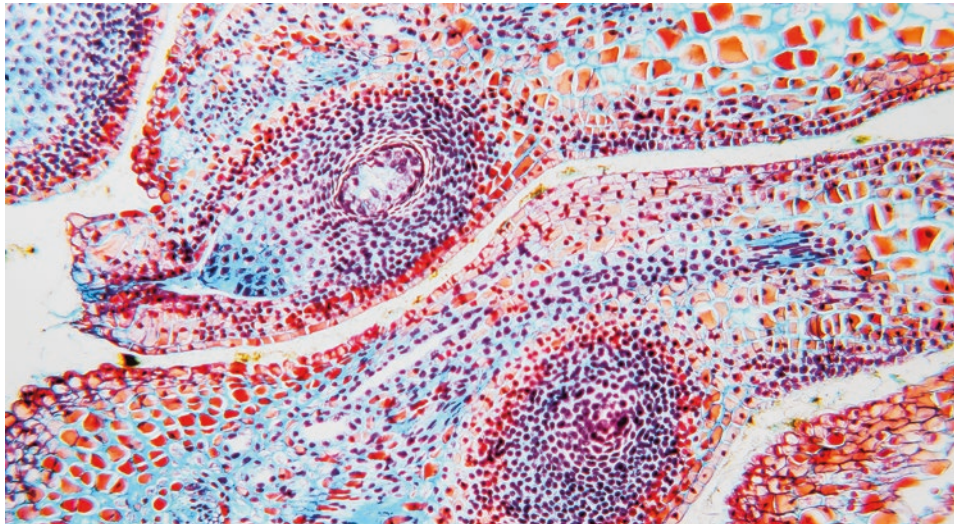
The study focuses on the development of nanocomposite W-C:H coatings with high hardness and simultaneously, with a lower coefficient of friction. Up to now, conventional optical microscopy, SEM/EDS, SEM/FIB and Raman spectroscopy were used to evaluate different aspects of the transfer layer formation. However, the information obtained with the Sensofar 3D optical profilometer, was newly introduced which provided further qualitative and quantitative information about the transfer layer within the whole contact area.



**MICROELECTRONICS**

# Measurements of the initial deflection of a nano pressure sensor for biological applications

In the fabrication of nano pressure sensors for biological applications, the sacrificial layer etching and the sealing of the two membranes separated by a vacuum gap is critical. Knowing the exact timing of the initial deflection of the membrane after the fabrication process is also key. As samples must be under vacuum pressure, measurements with a SEM may alter their initial state. That's why we chose Sensofar's S neox, since we were able to image and measure, in a quick non-destructive way, the deflection of the membranes after manufacturing.



**CONSUMER ELECTRONICS**

# Laser structuring of organic optoelectronic devices

To build large-scale organic light emitting diodes (OLEDs) for luminaires requires an invisible series of connections to reduce the device's current and then to mitigate ohmic losses. Laser-etched lines some with a width of a few micrometers and a depth of about 100 nm were monitored. The S neox allows us to detect if the removal process worked by measuring the thin film layers.



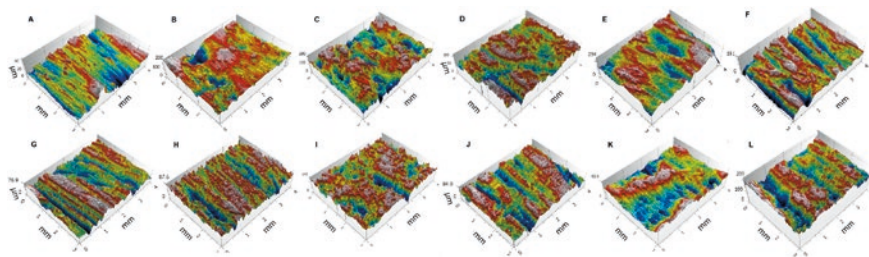
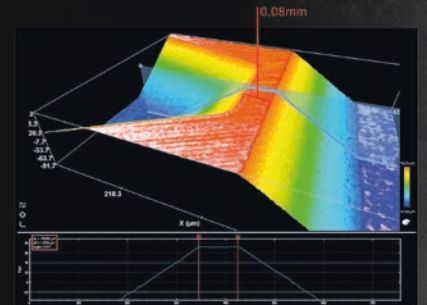
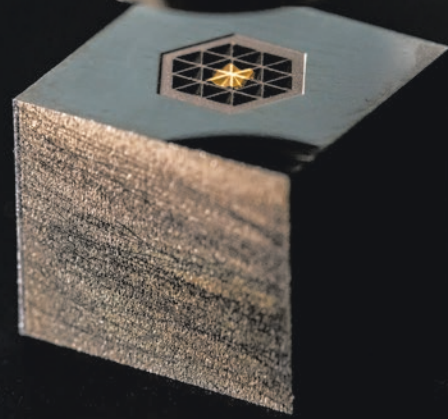


## MICROMANUFACTURING

# Measurements for femtosecond laser micro-milling and functional texturing

Sensofar's profiler has outstanding lateral resolution, which is a critical requirement to analyze nano structures over micro structures. This is necessary to be sure that the functional texturing will work properly based on the created texture. With the S neox, we are able to obtain fast and non-destructive measurements to assure the micro-millings are delivered within the correct tolerance.

microrelleus



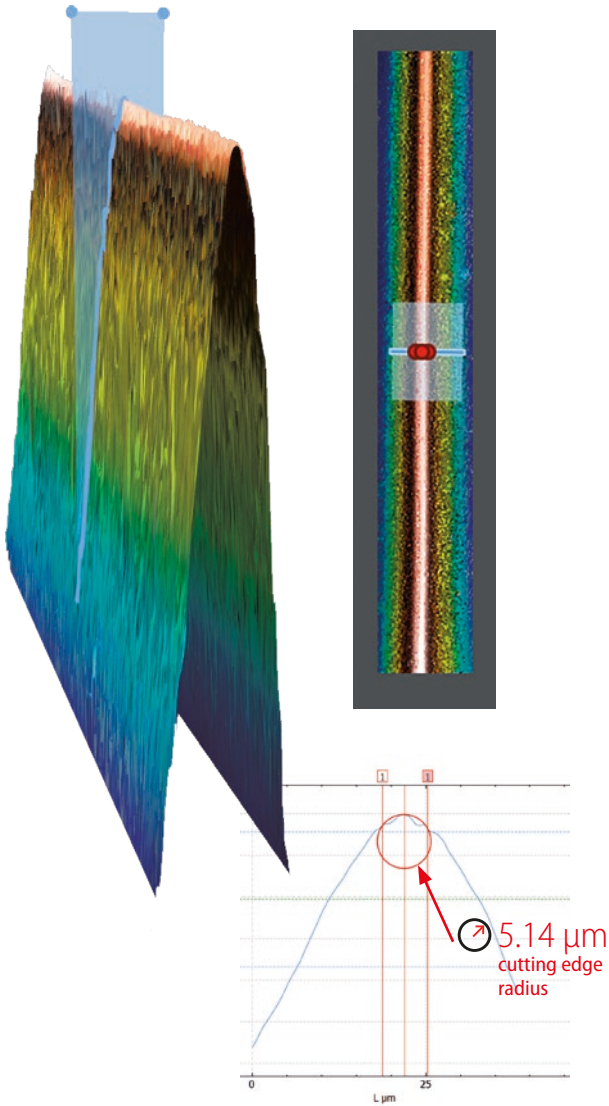
## ARCHAEOLOGY

# The use of ochre 40,000 years ago in Africa

To analyze pieces of iron-rich mineral fragments and identify facets of ochre pieces ground on different rocks, the Confocal technology was an ideal technique. With the ability of the S neox to measure large areas and large objects, and the set of filters to treat the 3D images, we are able to focus on the roughness of the usewear. It provides key information on the use of these pigments in those societies, and help establish their function through time and when they were first used symbolically in the history of mankind.

université  
de BORDEAUX





**MICROMANUFACTURING**

Cutting edge measurement of an insert

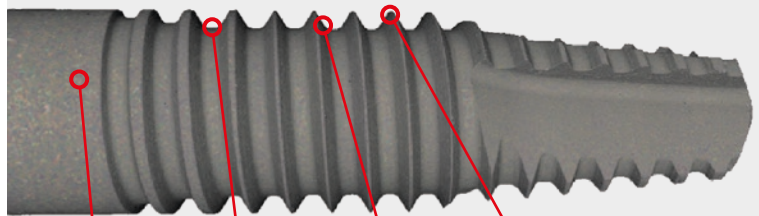
Whirling inserts are used to produce threads. The whirling process is complex, that's why there are many different angles (lead angle, angle of rake, clearance angle) on an insert. The 3D optical profilometer S neox Five Axis makes it possible to quickly and flexibly obtain the key parameters necessary for the continuous improvement of our tools, such as the cutting edge radius, clearance and rake angles, or even the roughness at the edge.



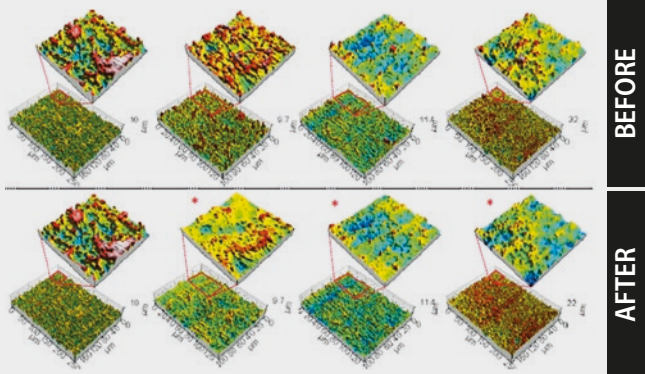
**MEDICAL DEVICES**

The effect of surgical insertion on dental implant surface topography

Implant research has been focused on the development of new surface treatments to increase surface roughness, aiming to enhance the biological response and ultimately, the osteointegration. The study came to the conclusion that Sensofar's S neox's Confocal technology is an effective technique to characterize different locations on a complex threaded dental implant with high resolution.



NECK VALLEY FLANK TOP





# Hardware

## **Motorized tip-tilt**

The motorized tip-tilt has been designed to automatically level the sample in less than 3s. This device reduces sample preparation time, and allows sample leveling in multiple positions for automated applications. The auto-tilt function can be used with all imaging techniques.

## Motorized nosepiece

The motorized nosepiece can hold up to six objectives simultaneously, including brightfield and interferometry objectives. The SensoSCAN software handles the motorized change automatically and corrects automatically any possible parfocality adjustment.



## Stand structure

The S neox is a complete tool. Its design is ideal for obtaining a fast, non-invasive assessment of the micro- and nanogeometry of technical surfaces in multiple configurations. S neox provides the flexibility, durability and efficiency required from the standard setup for R&D and quality inspection laboratories to sophisticated, customized solutions for online process controls, measuring samples up to 300x300 mm<sup>2</sup> and maximum height up to 350 mm.

## Ring light

The ring light is based on an LED ring for illuminating samples in a uniform and efficient way. Mounted above and around the objective, the ring light provides increased signal for the Ai Focus Variation technique. This ensures proper illumination at the focal plane.

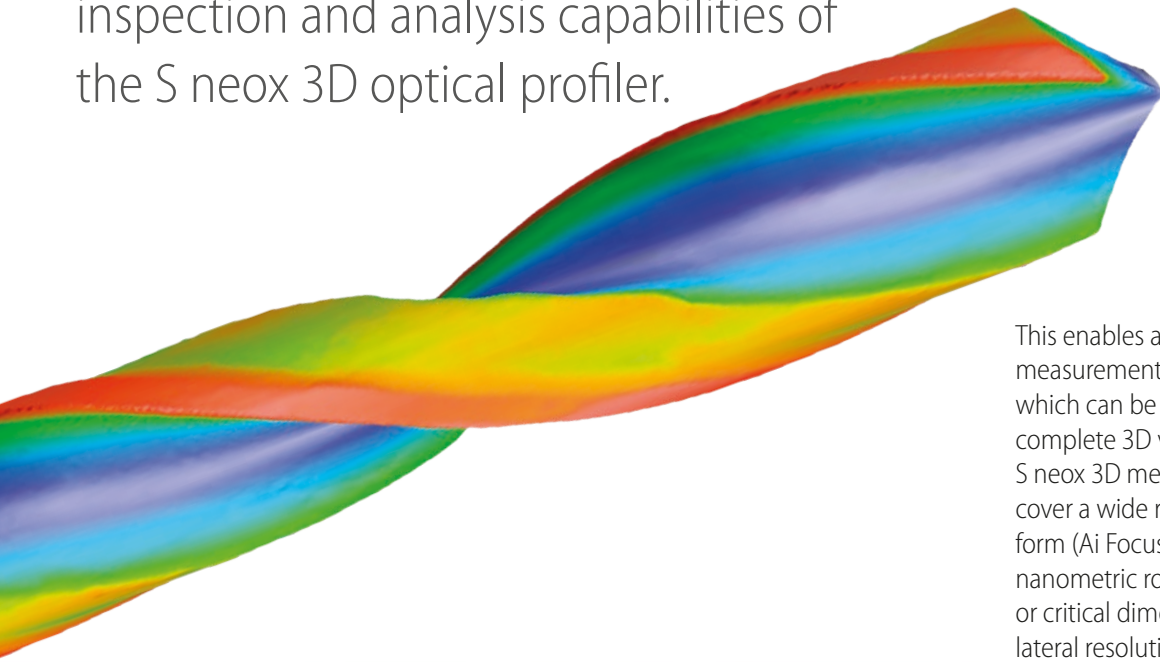




# Complete accessibility



The **S neox Five Axis 3D optical profiler** combines a high-accuracy rotational module with the advanced inspection and analysis capabilities of the S neox 3D optical profiler.



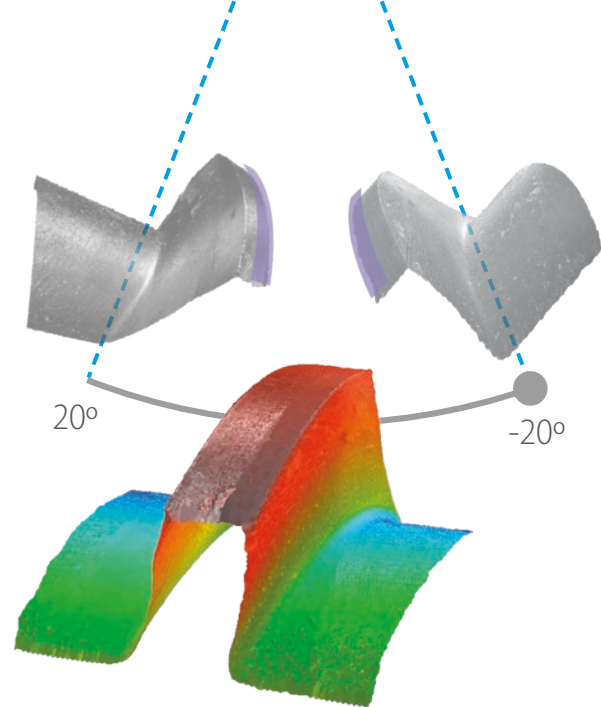
This enables automatic 3D surface measurements at defined positions which can be combined to create a complete 3D volumetric measurement. S neox 3D measurement technologies cover a wide range of scales, including form (Ai Focus Variation), sub nanometric roughness (Interferometry) or critical dimensions that require high lateral resolution as well as vertical resolution (Confocal).



## Rotational stage

The Five Axis rotational stage consists of a high-precision motorized rotating A axis with 360° of endless rotation, 10 arc sec positioning repeatability, a motorized B axis, -30° to 110°, 0.5 arc sec resolution, with limit switch. It is equipped with a System3R clamping system.

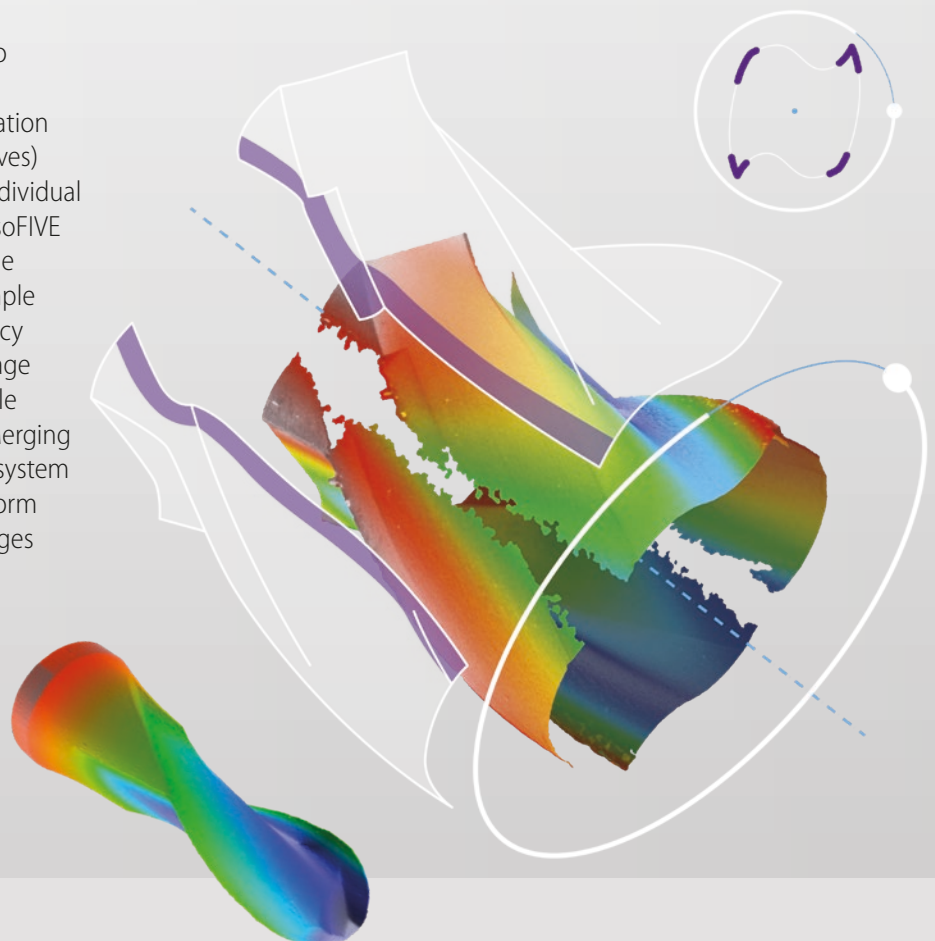
The S neox Five Axis makes it possible to take automatic 3D surface measurements at defined positions, and combine them to create a complete 3D volumetric measurement



# A complete 3D measurement



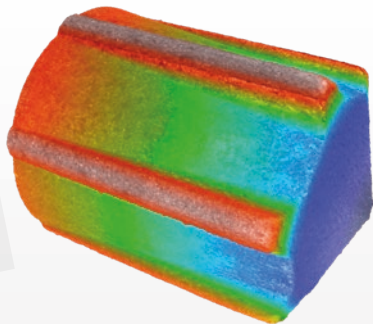
S neox Five Axis is able to measure the sample at different positions of rotation and elevation (perspectives) generating a group of individual measurements. The SensoFIVE software merges all of the surfaces providing a sample surface with high accuracy by using the stacked image information of each single surface measurement. Merging different elevations, the system can provide shape and form information on sharp edges and/or critical surfaces.





## Connecting adjoining surfaces to measure angles greater than 90°

Measuring complex surfaces which contain steep angles is very difficult due to shadowing effects that prevent you from obtaining a complete measurement within a single acquisition. It is necessary to tilt the sample in order to measure it from two different positions and combine the two topography results to obtain the complete measurement. Five Axis rotational stage allows the sample to be positioned in opposite directions to make the entire surface visible. The system will acquire the individual measurements and then, it will merge them automatically to get the complete 3D volumetric measurement.



## Multiple axis positions, measurements without limitation

Measuring different parts of the sample with one click is possible thanks to automation routines. A user-friendly interface allows you to find the measurement position without any constraints. Then focus on the critical parts of your sample and add them to the automation routine. Finally click Acquire to obtain all parts measured with one single click. This is an incredibly fast and easy way to automate the measurement routines.



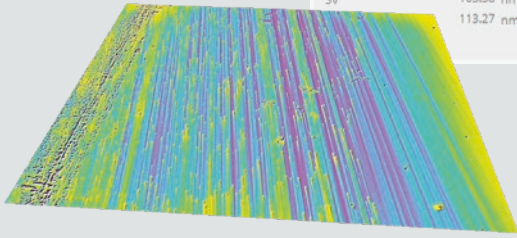


The **S neox Five Axis**  
is the most comprehensive  
and complete solution  
in the market for micro- and  
nano- scale imaging



Maxim

ISO 25178 / Height	
Sa	0.9742 nm
Sku	633.0968
Smean	-0.2042 nm
Sp	9.8887 nm
Sq	3.2244 nm
Ssk	22.8511
Sv	103.38 nm
Sv	113.27 nm



## Accurate and reliable surface finish measurements

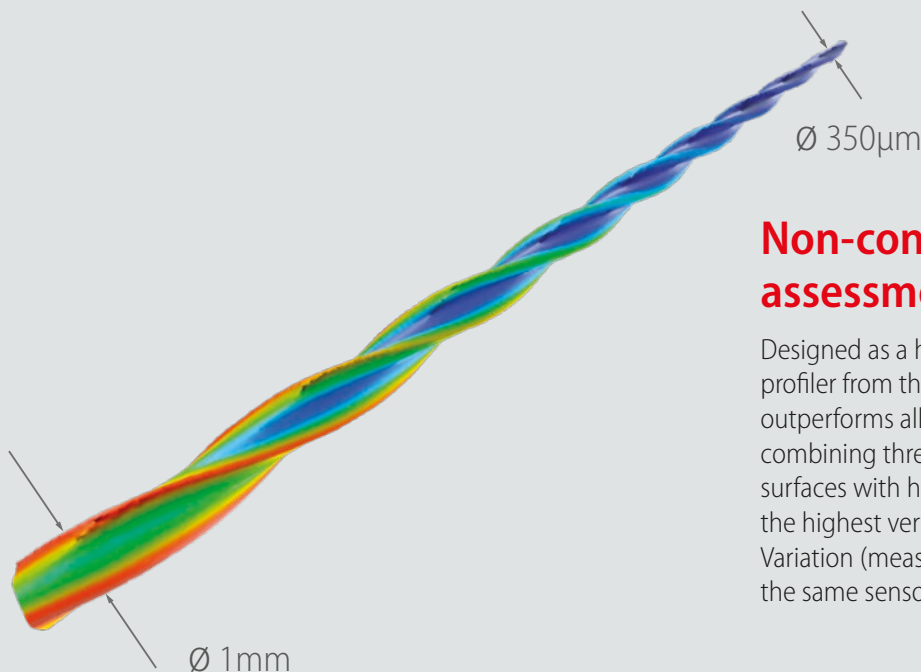
Our Confocal and Interferometry technologies allow you to measure surfaces with any kind of roughness from extremely rough (typical of additive manufacturing applications) to highly reflective surfaces of the order of 1 Å as a diamond mirror-like surface. Converting our system into repetitive and traceable, according to NPL, NIST and PTB roughness standards. Ai Focus Variation technology provides a quick and easy response for measuring outstanding slopes independently of the objective lenses.



## Overcoming the limitations of Focus Variation

S neox Five Axis is able to measure the shape and surface finish. Focusing on the shape, the system is able to measure samples with small diameters up to 0.5 mm and cutting edge radius up to 150 nm. Confocal technology and high numerical apertural (0.95) allows you to measure small cutting edge radius.

# um versatility



## Non-contact surface assessment

Designed as a high-performance 3D optical profiler from the outset, S neox Five Axis outperforms all existing optical profilers by combining three techniques – Confocal (best for surfaces with high slope), Interferometry (yields the highest vertical resolution) and Ai Focus Variation (measure shape in mere seconds) – in the same sensor head without any moving parts.



# Specifications

## Objective lenses

MAG	Brightfield																
	1X EPI	2.5X EPI	5X EPI	10X EPI	20X EPI	20X EPI	50X EPI	50X EPI	50X EPI	100X EPI	100X EPI	100X EPI	150X EPI	150X EPI	20X ELWD	50X ELWD	100X ELWD
NA	0.03	0.075	0.15	0.30	0.45	0.70	0.80	0.80	0.95	0.90	0.90	0.95	0.90	0.95	0.40	0.60	0.80
WD (mm)	3.80	6.50	23.5	17.5	4.5	2.3	1.0	2.0	0.35	1.0	2.0	0.32	1.5	0.2	19	11	4.5
Spatial sampling <sup>1</sup> (μm)	6.90	2.76	1.38	0.69	0.34	0.34	0.13	0.13	0.13	0.07	0.07	0.07	0.05	0.05	0.34	0.13	0.07
Optical resolution <sup>2</sup> (μm)	4.68	1.87	0.94	0.47	0.31	0.20	0.18	0.18	0.15	0.16	0.16	0.15	0.156	0.148	0.35	0.23	0.18
System noise <sup>3</sup> (nm)	–	300	100	30	8	5	4	4	3	3	3	2	2	1	10	5	3
Maximum slope <sup>4</sup> (°)	2	4	9	17	27	44	53	53	72	64	64	72	64	72	24	37	53

## Linnik

MAG	1X EPI	2.5X EPI	5X EPI	10X EPI	20X EPI	50X ELWD	50X SLWD
NA	0.03	0.075	0.15	0.30	0.45	0.60	0.40
WD (mm)	3.80	6.50	23.5	17.5	4.5	11.0	22.0

## System specifications

Measuring principle	Confocal, PSI, ePSI, CSI, Ai Focus Variation and Thin Film
Observation types	Brightfield, DIC, Sequential Color RGB, Confocal, Interferential Phase Contrast
Measurement types	Image, 3D, 3D thickness, profile and coordinates
Camera	5Mpx: 2448x2048 pixels (60 fps)
Total magnification (27" screen)	60X - 21600X
Display resolution	0.001 nm
Field of view	from 0.018 to 6.7 mm (single shot)
Max. Extended measuring area	10x12 (Max. Resolution); 175x175 (Low resolution) (500 Mpx)
Confocal frame rate	60 fps (5Mpx); 180 fps (1.2 Mpx)
Vertical scan range coarse	Linear stage: 40 mm range; 5 nm resolution
Vertical scan range fine	Piezoelectric scanner with capacitive sensor: 200 μm range; 1.25 nm resolution
Max. Z measuring range	PSI 20 μm; CSI 10 mm; Confocal & Ai Focus Variation 34 mm
XY stage range	Manual: 40x40 mm; Motorized: 114x75 mm, 154x154 mm, 255x215 mm, 302x302 mm
LED light sources	Red (630 nm); green (530 nm); blue (460 nm) and white (575 nm; center)
Ring light illumination	Green ring light compatible with 6 position nosepiece
Nosepiece	6 position fully motorized
Sample reflectivity	0.05 % to 100%
Sample weight	up to 25 Kg
Sample height	40 mm (standard); 150 mm and 350 mm (optional)
User Management rights	Administrator, supervisor, advanced operator, operator
Advanced Software Analysis	SensoMAP, SensoPRO, SensoMATCH, SensoCOMP (optional)
Power	Line Voltage 100-240 V AC; frequency 50/60 Hz single phase
Computer	Latest INTEL processor; 3840x2160 pixels resolution (4K) (27")
Operating system	Microsoft Windows 10, 64 bit
Dimensions	System: 600x610x740 mm (23.6x24x29.1 in); Controller: 209x318x343 mm (8.2x12.5x 13.5 in)
Weight <sup>9</sup>	61 Kg (134 lbs)
Environment	Temperature 10 °C to 35 °C; Humidity <80 % RH; Altitude <2000 m

## Accuracy and repeatability<sup>6</sup>

Standard	Value	U, σ	Technique
Step height	48600 nm	U=300 nm, σ= 10 nm	Confocal & CSI
	7616 nm	U=79 nm, σ= 5 nm	Confocal & CSI
	941.6 nm	U=7 nm, σ= 1 nm	Confocal & CSI
Areal roughness (Sa) <sup>7</sup>	186 nm	U=4 nm, σ= 0.4 nm	Confocal & CSI
	44.3 nm	U=0.5 nm, σ= 0.1 nm	PSI
	10.8 nm	U=0.5 nm, σ= 0.05 nm	PSI
	0.79 μm	U=0.04 μm, σ=0.0005 μm	Confocal, AiFV & CSI
	2.40 μm	U=0.03 μm, σ= 0.002 μm	Confocal, AiFV & CSI
Profile roughness (Ra) <sup>8</sup>	0.88 μm	U=0.015 μm, σ= 0.0005 μm	Confocal, AiFV & CSI
	0.23 μm	U=0.005 μm, σ= 0.0002 μm	Confocal, AiFV & CSI

**1** Pixel size on the surface. **2** L&S: Line and Space. Values for blue LED. **3** System noise measured as the difference between two consecutive measures on a calibration mirror placed perpendicular to the optical axis. For interferometry objectives, PSI, 10 phase averages, values obtained in a VC-E vibration environment. The 0.01 nm are achieved with Piezo stage scanner and temperature controlled room. Values for green LED (white LED for CSI). Resolution HD. **4** On smooth surfaces, up to 71°. On scattering surfaces, up to 86°. **5** Maximum field of view with 3/2" camera and 0.5X optics. **6** Objective used for Confocal and Ai Focus Variation 50X 0.80 NA and for CSI and PSI 50X 0.55NA. Resolution 1220x1024 pixels. All measurements are done using PZT. Uncertainty (U) according to ISO/IEC guide 98-3:2008 GUM:1995, K=1,96 (level of confidence 95%). σ according to 25 measures. **7** Area of 1x1 mm. **8** Profile of 4 mm length. **9** Fixed stand with H101 XY Stage.

Water immersion

Collar ring

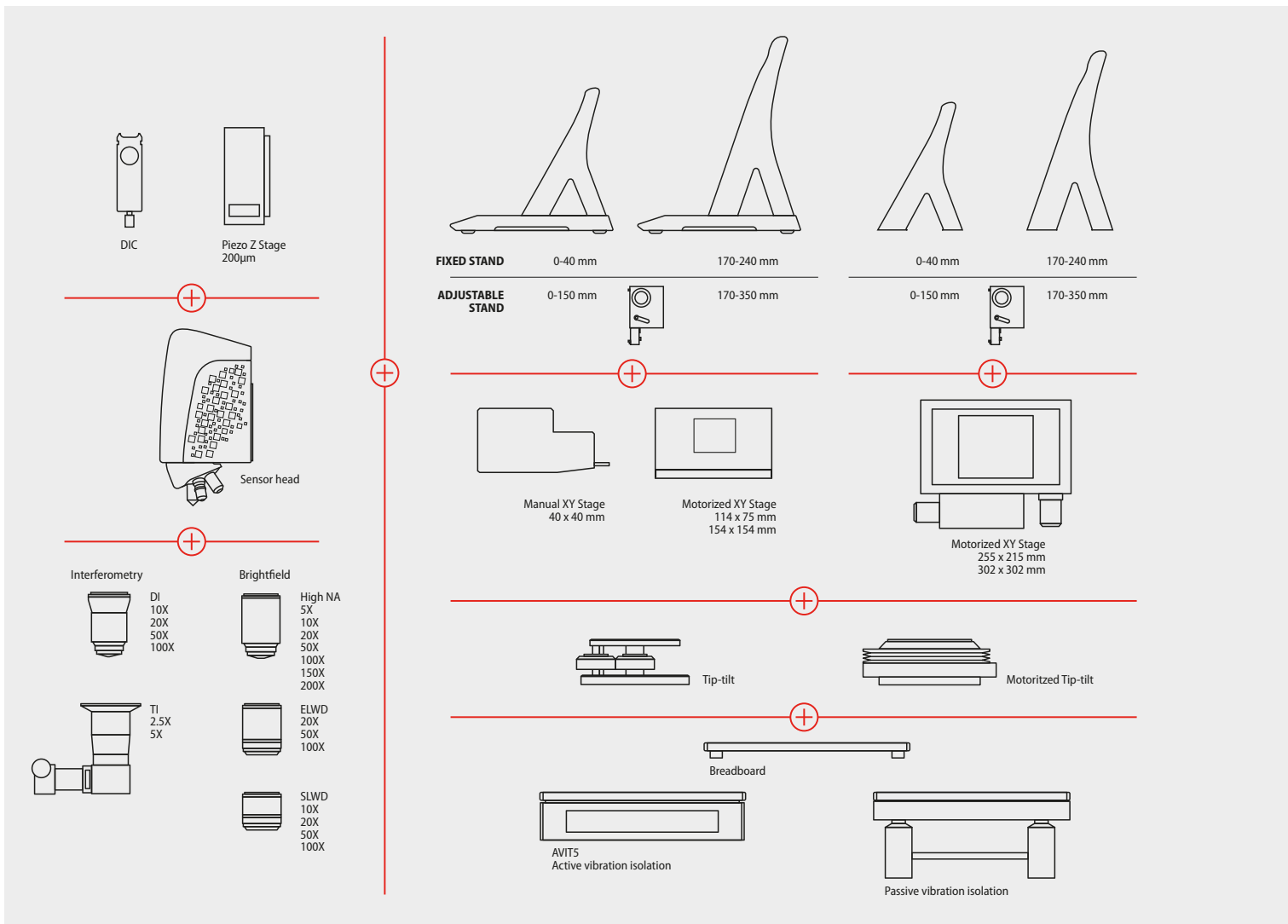
Oil immersion

Interferometry

10X SLWD	20X SLWD	50X SLWD	100X SLWD	10X WI	20X WI	63X WI	20X EPI CR	50X EPI CR	100X EPI CRA	100X EPI CRB	50X OI	100X OI	2.5X	5X	10X	20X	50X	100X
0.20	0.30	0.40	0.60	0.30	0.50	1.00	0.45	0.70	0.85	0.85	0.9	1.4	0.075	0.13	0.30	0.40	0.55	0.70
37	30	22	10	3.50	3.30	2.00	10.9–10.0	3.9–3.0	1.2–0.85	1.3–0.95	0.35	0.16	10.3	9.3	7.4	4.7	3.4	2.0
0.69	0.34	0.13	0.07	0.69	0.35	0.11	0.35	0.138	0.07	0.07	0.14	0.07	2.76	1.38	0.69	0.34	0.13	0.07
0.70	0.47	0.35	0.23	0.47	0.28	0.14	0.31	0.20	0.17	0.17	0.21	0.14	1.87	1.08	0.47	0.35	0.26	0.20
50	20	15	10	–	–	–	–	–	–	–	–	–	PSI/ePSI 0.1 nm (0.01 nm with PZT) CSI 1 nm					
12	17	24	37	17	30	90	27	44	58	58	64	–	4	7	17	24	33	44

MAG	1X	2.5X	5X	10X	20X	50X	63X	100X	150X
FOV <sup>z</sup> ( $\mu$ m)	16890x14130	6756x5652	3378x2826	1689x1413	845x707	338x283	268x224	169x141	113x94

System configuration





SENSOFAR is a leading-edge technology company that has the highest quality standards within the field of surface metrology

Sensofar Metrology provides high-accuracy optical profilers based on confocal, interferometry, focus variation and fringe projection techniques, from standard setups for R&D and quality inspection laboratories to complete non-contact metrology solutions for in-line production processes. The Sensofar Group has its headquarters in Barcelona, also known as a technology and innovation hub in Europe. The Group is represented in over 30 countries through a global network of partners and has its own offices in Asia, Germany and the United States.

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